



Design and optimization techniques for a nano-positioning system

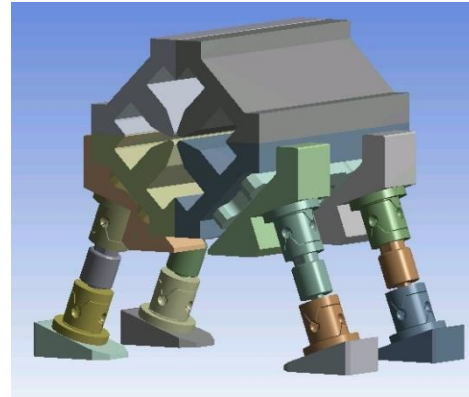
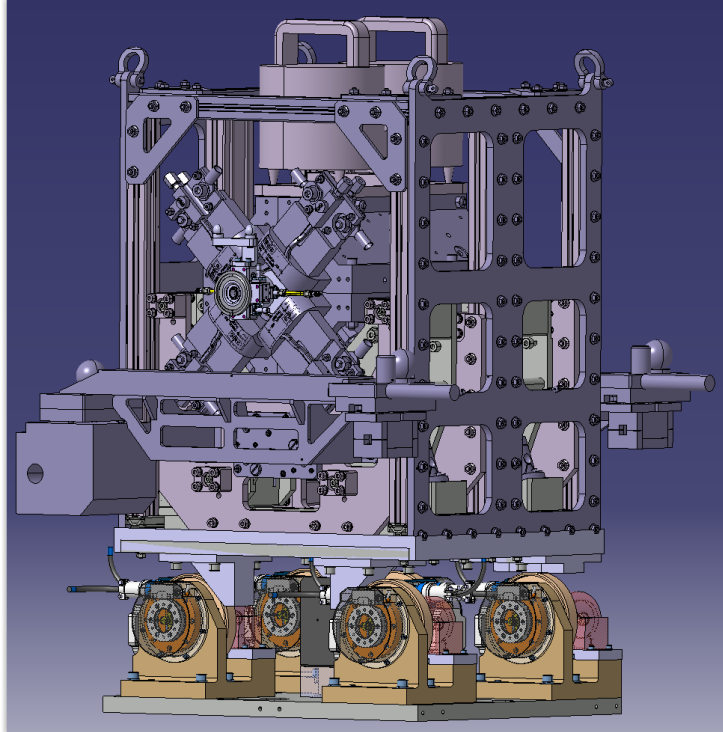
D. Tshilumba, K. Artoos, J. Spronck



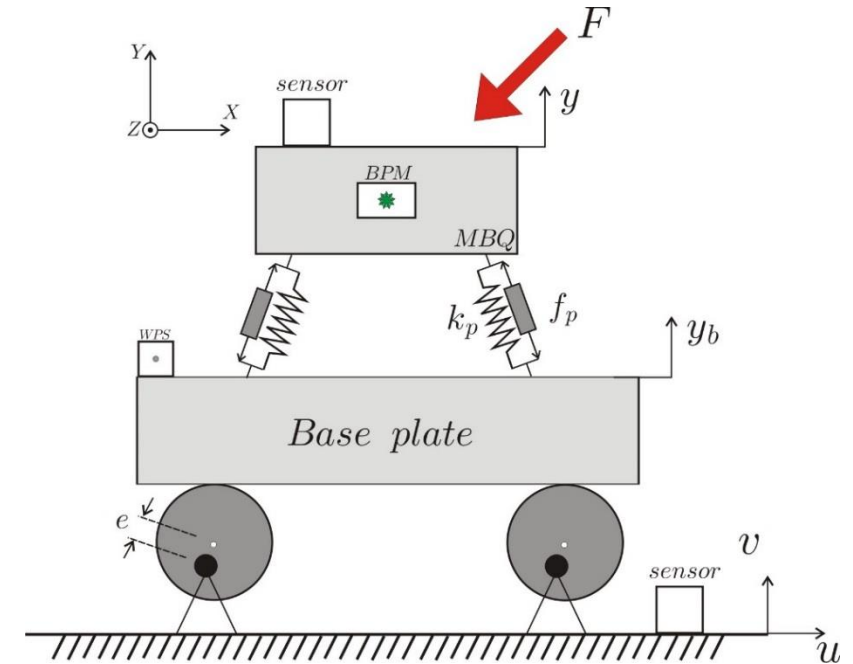


- Context and research objectives
- Matlab toolbox for Compliance matrix method
- CATIA- ANSYS parametric modelling
- Fem-based State space model extraction of Multiple inputs multiple output dynamic systems
- Conclusion and next steps

3 Current system overview



Magnet mass: 80kg



Coarse stage (cams)

- locked after pre-alignment
- Resolution : $0.35\mu\text{m}$
- Stroke: 3mm

Fine stage (piezo stacks)

- Resolution: 0.15nm
- Stiffness : $480\text{N}/\mu\text{m}$
- Useful Stroke: $10\mu\text{m}$

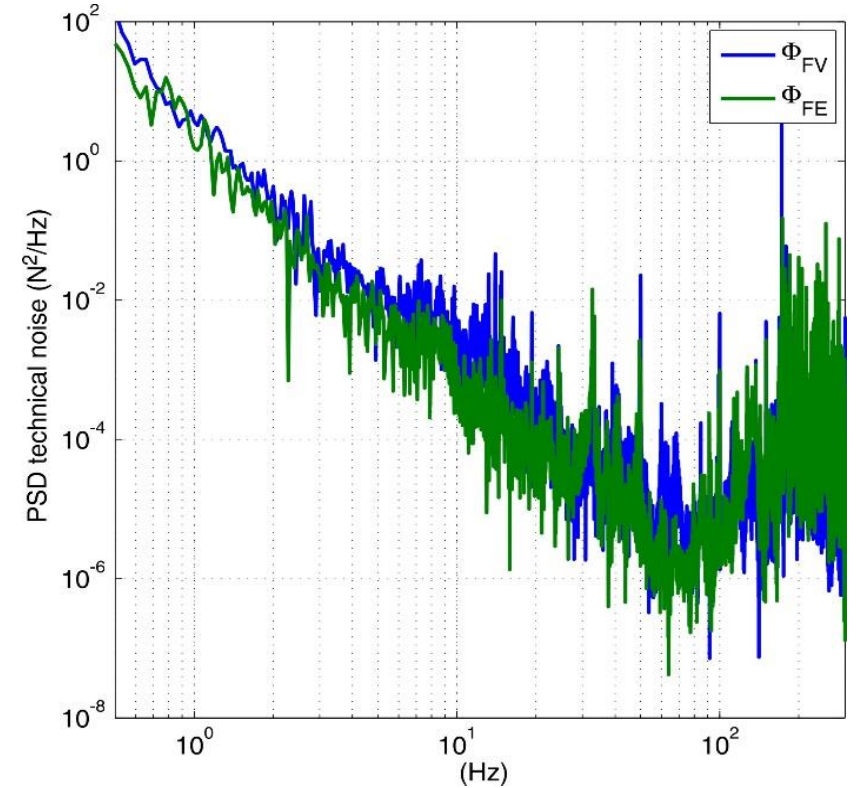
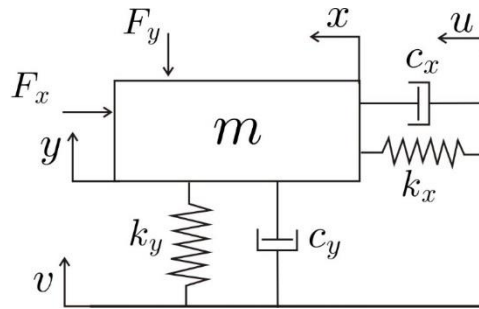
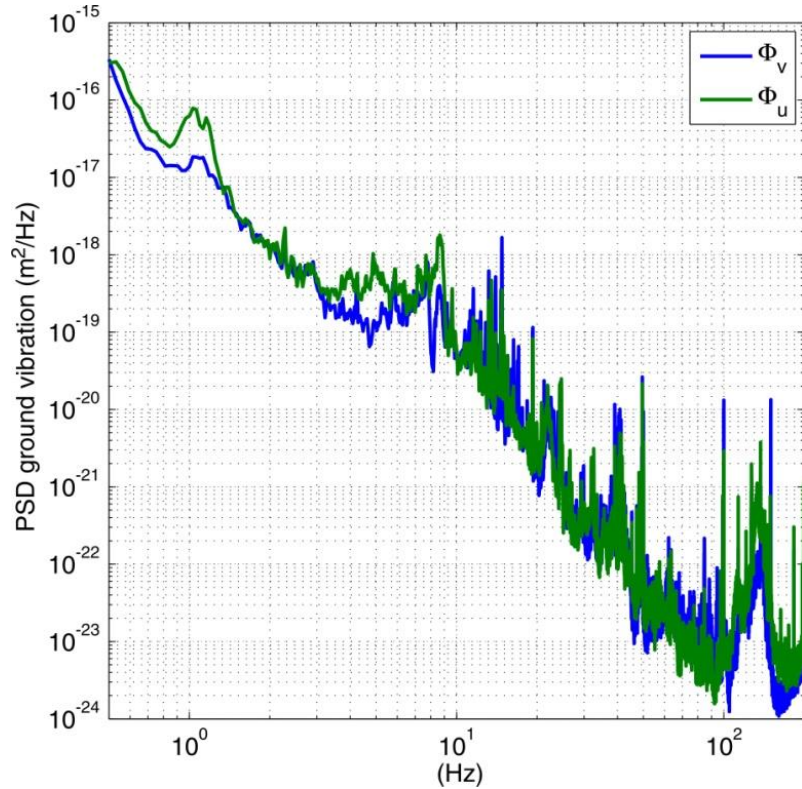
Limitations:

- ~50 days of operation using fine stage only
- insufficient stroke of fine stage for thermal load compensation in tunnel ($>100\mu\text{m}$)
- Limited precision of coarse stage ($1\mu\text{m}$ achievable after several iterations)



Upgrade of existing type 1 module
Alternative concept for long range actuator

4 Disturbance sources on CLIC MBQ



- Ground motion
- External forces (Water cooling, ventilation,...)
- Stiff connection to the rock

5 Phases in magnet life cycle + Positioning stage requirements

Functions :

- ❑ 5dofs Alignment (before beam)
- ❑ 2dofs Nanopositioning (beam-based alignment phase + nominal beam operation phase)
- ❑ 2dofs Vibration isolation (nominal beam operation phase)
 Stability requirements: 1.5nm rms @ 1 Hz (vertical)
 5nm rms @ 1 Hz (lateral)

Study of an integrated positioning system with **high stiffness** ($>100\text{N}/\mu\text{m}$) capable of moving **heavy loads** ($>50\text{ kg}$) with **high resolution** ($<1\text{nm}$) over a **large range** ($\geq 1\text{mm}$)

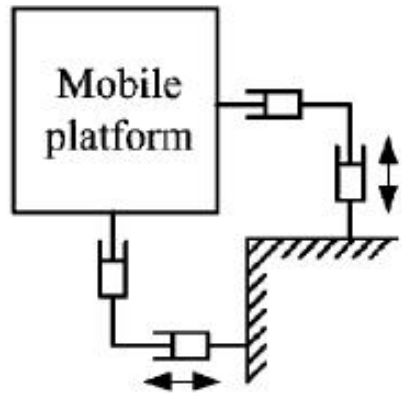
Parameters	Value
Resolution	$<0.25\text{nm}$
step displacement	0.25 up to 50nm
Stroke	$\pm 3\text{mm}$
Pitch angle	$6\mu\text{rad}$
Yaw angle	$6\mu\text{rad}$
Roll angle Max	$100\mu\text{rad}$
Speed	$\geq 50\mu\text{m/s}$
Settling time $t_1 \rightarrow t_2$	$10\text{ms} \leq t_s \leq 15\text{ms}$
On-axis stiffness (vertical/lateral)	$400\text{ N}/\mu\text{m}$
Force capacity (positioning)	$5\text{N}+20\text{N}$
Force capacity (isolation)	10N



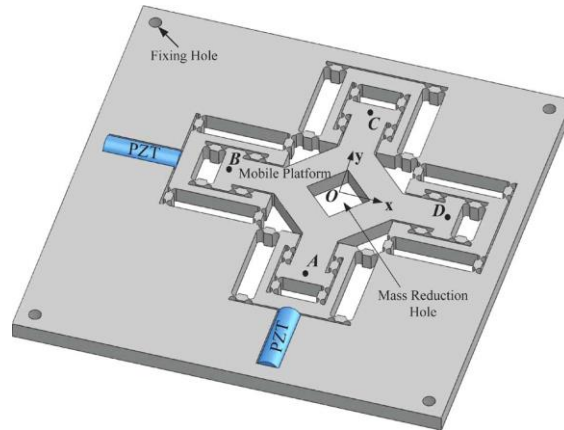
Compliance matrix method

7 Conceptual design of a nano-positioning system

- ❑ Most of decoupled XY stages based on 2PP mechanism
- ❑ Depending on requirement each module can be built out of notches or leaf springs
- ❑ Y. Li, J. Huang, H. Tang, *A compliant parallel XY Micromotion stage with complete kinematic decoupling*

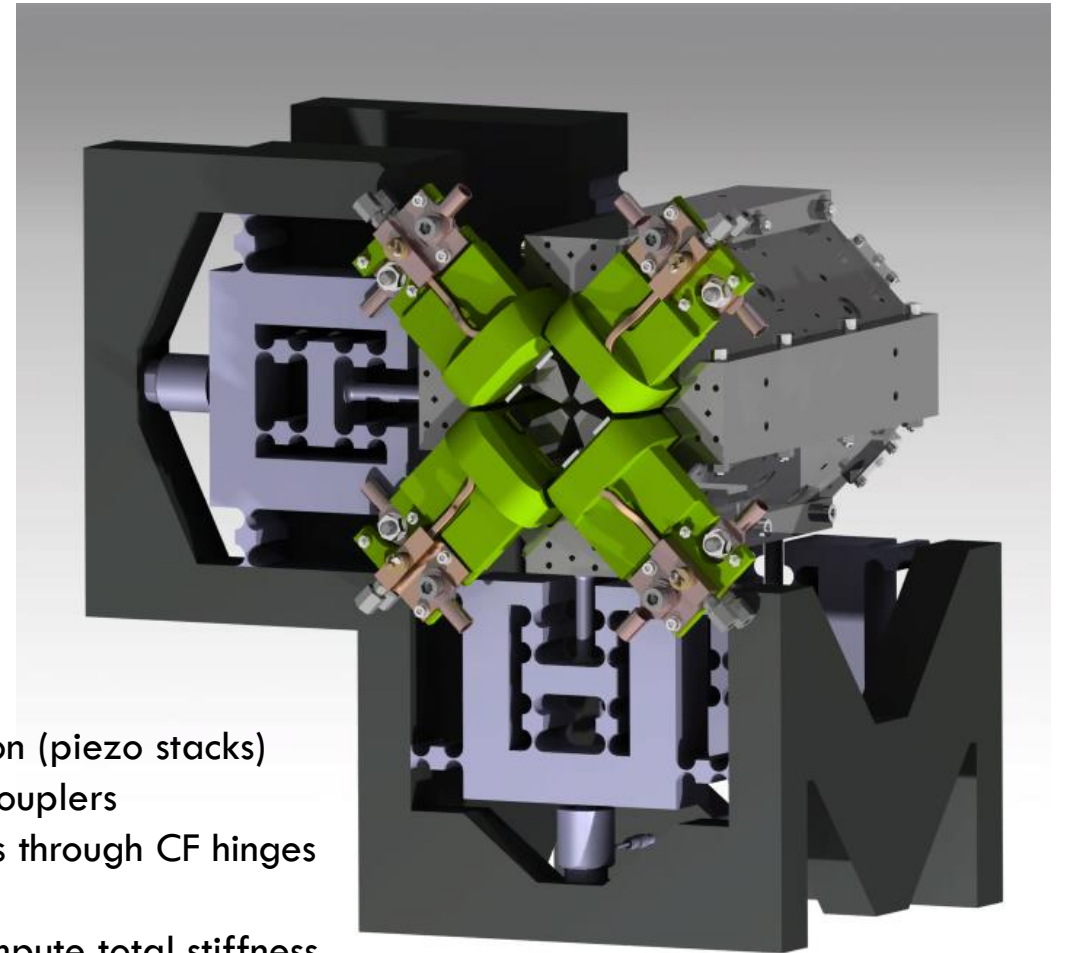


2PP mechanism



Courtesy of Y. Li

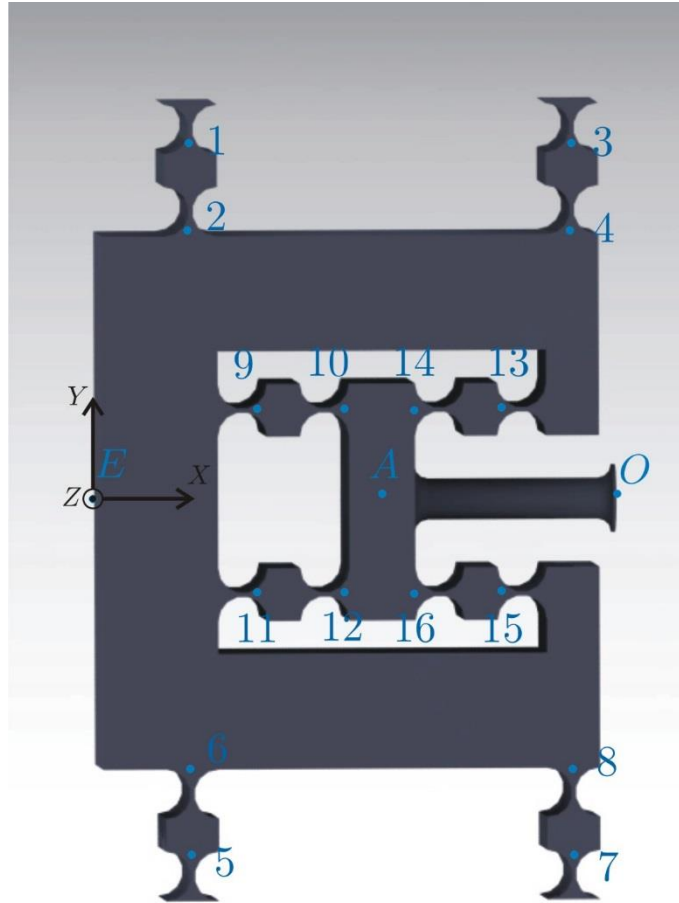
- ❑ 4 dofs actuation (piezo stacks)
- ❑ Compliant decouplers
- ❑ Rotational dofs through CF hinges compliance
- ❑ Objective: Compute total stiffness matrix



8 Compliance matrix method

- ❑ Overall compliance computation in 6 dofs at point of interest (i.e. O and E)
- ❑ Based on analytical compliance matrices of elementary hinges
- ❑ Boundary conditions: base of notch hinges 1,3,5,7 clamped
- ❑ Script validated on elementary hinges and sub-parts of the module

$$C = \begin{pmatrix} c_{x,Fx} & 0 & 0 & 0 & 0 & 0 \\ 0 & c_{y,Fy} & 0 & 0 & 0 & c_{rz,Fy} \\ 0 & 0 & c_{z,Fz} & 0 & c_{ry,Fz} & 0 \\ 0 & 0 & 0 & c_{rx,Mx} & 0 & 0 \\ 0 & 0 & c_{z,My} & 0 & c_{ry,My} & 0 \\ 0 & c_{y,Mz} & 0 & 0 & 0 & c_{rz,Mz} \end{pmatrix}$$



- ❑ Notch hinges dimensions:
 - $R = 7mm$
 - $t = 1mm$
 - $d = 50mm$
- ❑ CF hinge dimensions:
 - $L = 51.6mm$
 - $R = 6.2mm$
 - $r_f = 4.2mm$

❑ Material: structural steel

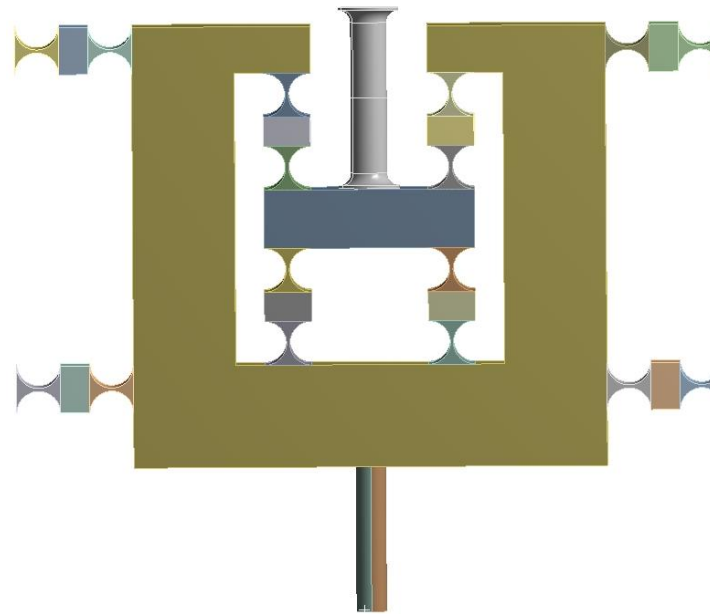
Output Compliance at point O (without actuator)

Input parameters	Analytical	FEA Flexible
On axis Compliance $c_{x,Fx}^O$	0.311um/N	0.293um/N
Transverse Compliance $c_{y,Fy}^O$	0.644um/N	0.611um/N
In-plane bending Compliance $c_{rz,Mz}^O$	2.92e-4rad/Nm	2.51e-4rad/Nm
In-plane bending Compliance $c_{y,Mz}^O$	1.02e-5m/Nm	7.8e-6m/Nm
Out-of-plane Compliance $c_{z,Fz}^O$	0.341um/N	0.328um/N
Out-of-plane Compliance $c_{ry,My}^O$	2.92e-4rad/Nm	2.52e-4rad/Nm
Out-of-plane Compliance $c_{z,My}^O$	1.02e-5m/Nm	7.8e-6m/Nm

9 Compliance matrix method

- Overall compliance computation in 6 dofs at point of interest (i.e. O and E)
- Based on analytical compliance matrices of elementary hinges
- Actuator modeled as a cylinder with the desired axial stiffness (e.g. 480N/um)
- Additional BC: base of actuator clamped

$$C = \begin{pmatrix} c_{x,Fx} & 0 & 0 & 0 & 0 & 0 \\ 0 & c_{y,Fy} & 0 & 0 & 0 & c_{rz,Fy} \\ 0 & 0 & c_{z,Fz} & 0 & c_{ry,Fz} & 0 \\ 0 & 0 & 0 & c_{rx,Mx} & 0 & 0 \\ 0 & 0 & c_{z,My} & 0 & c_{ry,My} & 0 \\ 0 & c_{y,Mz} & 0 & 0 & 0 & c_{rz,Mz} \end{pmatrix}$$

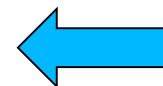


Output Compliance at point O (with actuator)

Input parameters	Analytical	FEA Flexible
On axis Compliance $c_{x,Fx}^O$	5.27nm/N	5.68nm/N
Transverse Compliance $c_{y,Fy}^O$	0.645um/N	0.611um/N
In-plane bending Compliance $c_{rz,Mz}^O$	2.92e-4rad/Nm	2.51e-4rad/Nm
In-plane bending Compliance $c_{y,Mz}^O$	1.02e-5m/Nm	7.8e-6m/Nm
Out-of-plane Compliance $c_{z,Fz}^O$	0.341um/N	0.328um/N
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Out-of-plane Compliance $c_{z,My}^O$	1.02e-5m/Nm	7.8e-6m/Nm

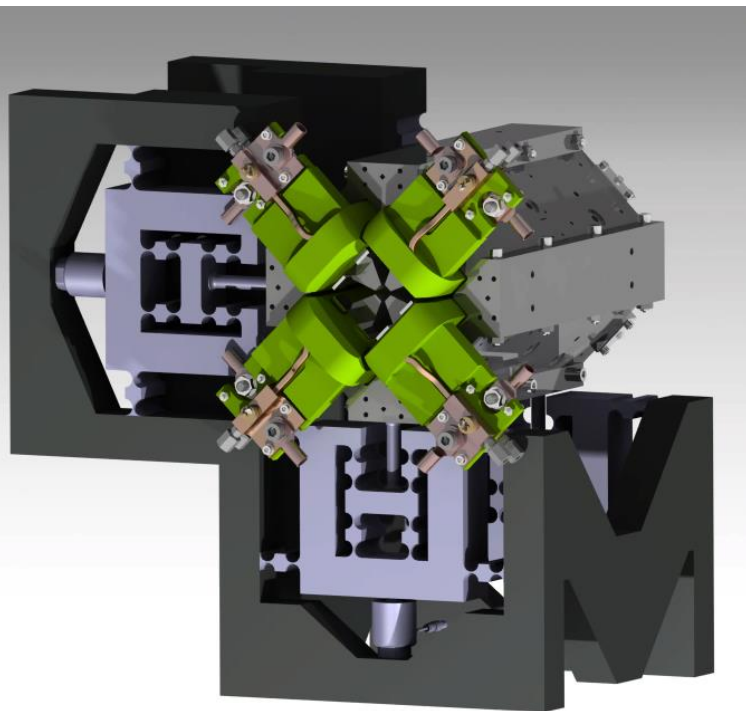
Input parameters	Analytical
On axis Stiffness $k_{x,Fx}^O$	190N/um
Transverse Stiffness $k_{y,Fy}^O$	3.47N/um
In-plane bending Stiffness $k_{rz,Mz}^O$	7.67kNm/rad
Out-of-plane Stiffness $k_{z,Fz}^O$	42N/um
Out-of-plane Stiffness $k_{ry,My}^O$	49.04kNm/rad

The requirement of static stiffness is almost reached!
(i.e. 200N/um per module in direction of actuation)

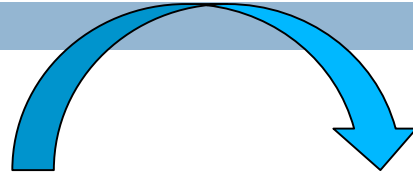




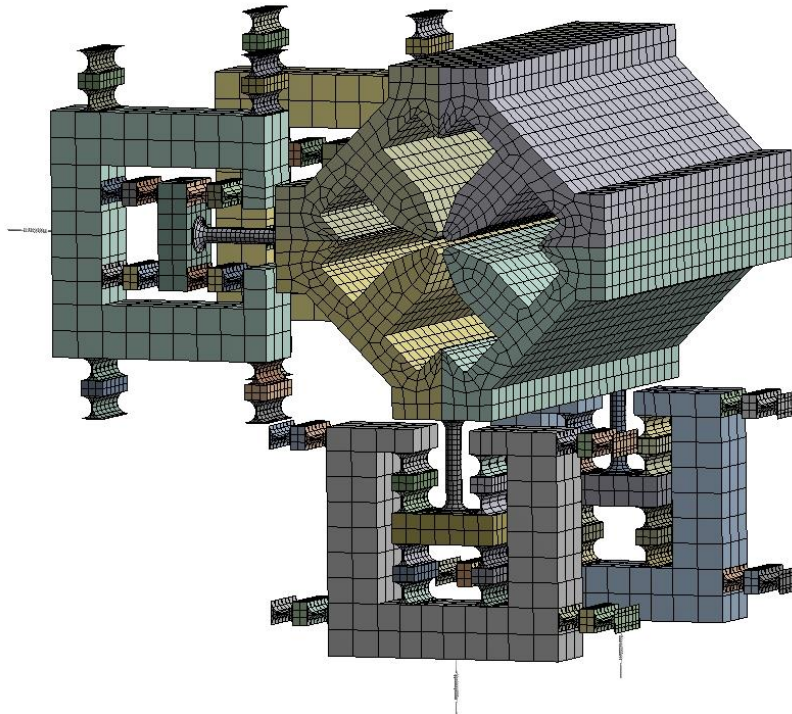
Parametric modelling



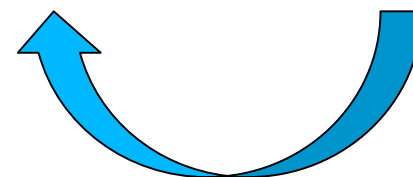
CATIA V5



CAD NEXUS



ANSYS WB



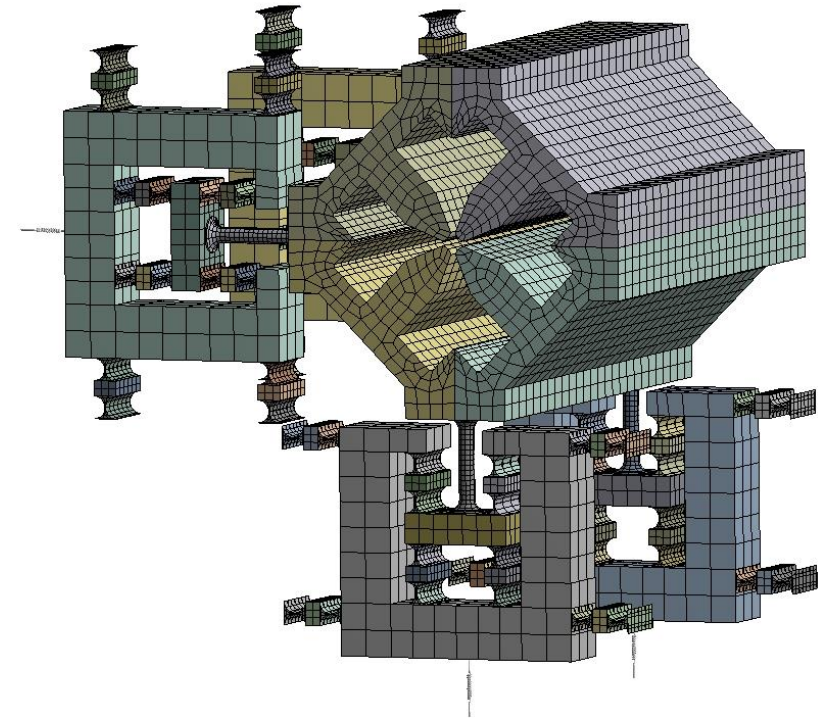
- ❑ CAD parameters exchange and bi-directional update
- ❑ Input parameters:
 - Remote magnet displacement (P2)
 - Notch hinges thickness (P4)
 - Diameter pillar (P5)
 - Fillet radius pillar (P6)
 - Notch hinges depth (P7)
- ❑ Output parameters:
 - Equivalent Max stress (P1)
 - First eigen frequency (P3)
 - Vertical magnet displacement (P8)

Powerful tool for automatized sensitivity and optimization study

12 Parametric modelling: Design of experiments

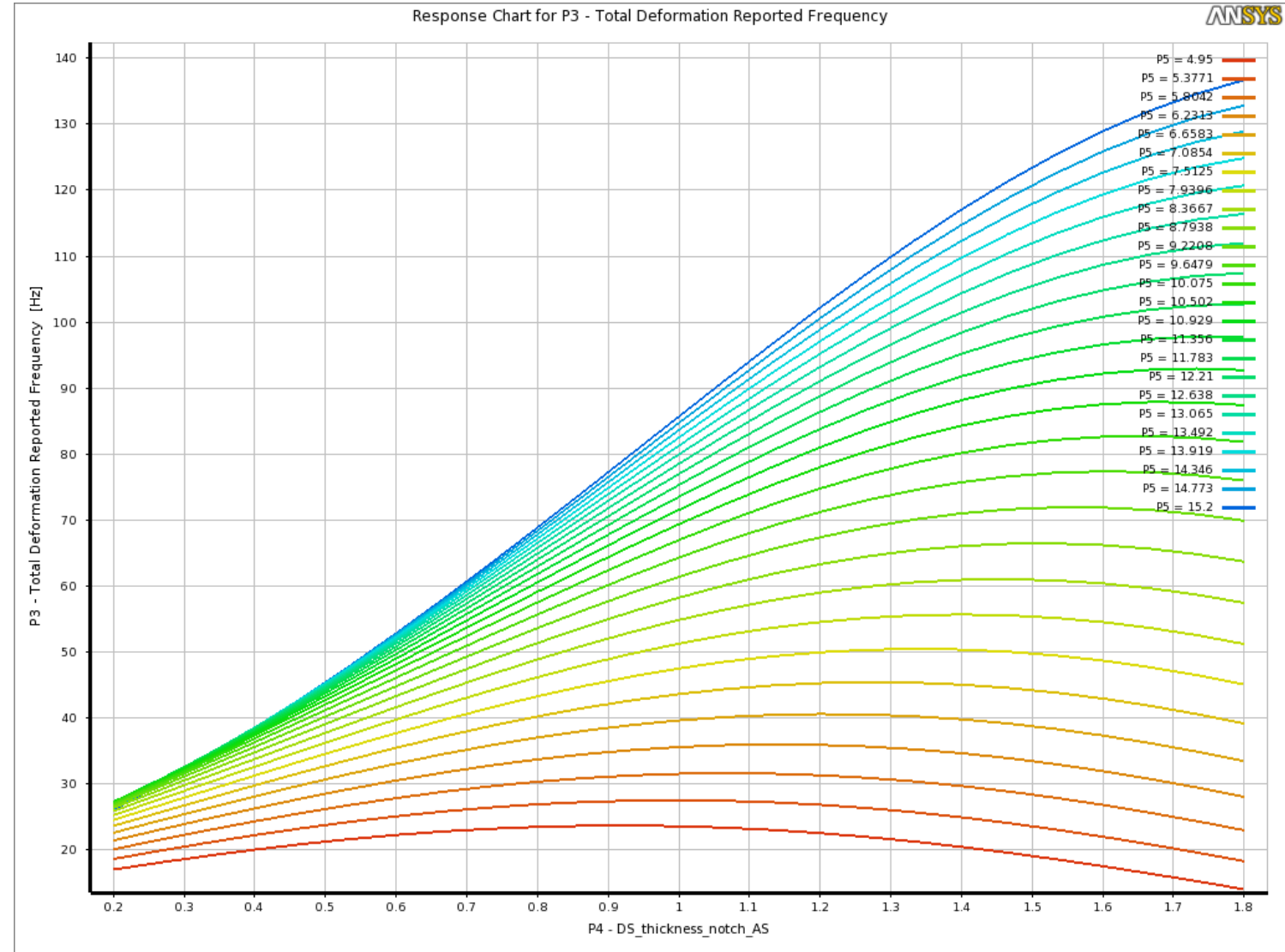
Design of experiments settings	
DOE type	Latin Hypercube Sampling design
Samples type	User-defined Samples
Number of samples	40

Design parameters range	
Remote magnet displacement (P2)	0.9 μm \rightarrow 20 μm
Notch hinges thickness (P4)	0.2 mm \rightarrow 1.8 mm
Pillars diameter (P5)	4.95 mm \rightarrow 15.2 mm
Pillars fillet radius (P6)	2 mm \rightarrow 7 mm
Notch hinges depth (P7)	30 mm \rightarrow 70 mm



14 Parametric modelling: Sensitivity study

- Lowest eigen frequency to P4 and P5
- Larger diameter → larger frequency increase in a fixed interval of notch thickness
- Asymptotic limit of diameter contribution to the frequency
- Local maximum for a fixed diameter value



15 Parametric modelling: Optimization

Desired output results from optimizer:

- Pillars dimensions
- Notch hinges dimensions

Pb: Minimize magnet displacement (P8)

With constraints:

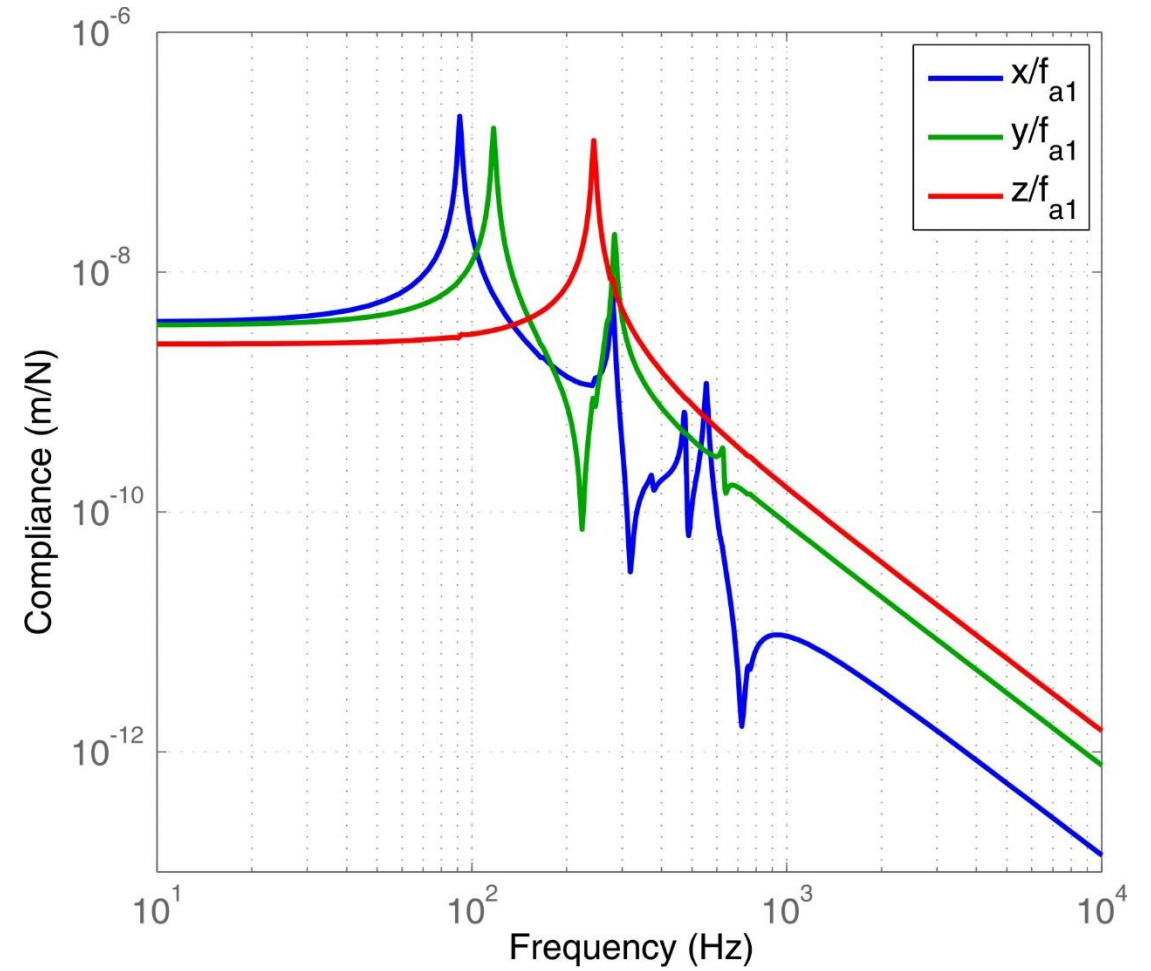
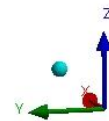
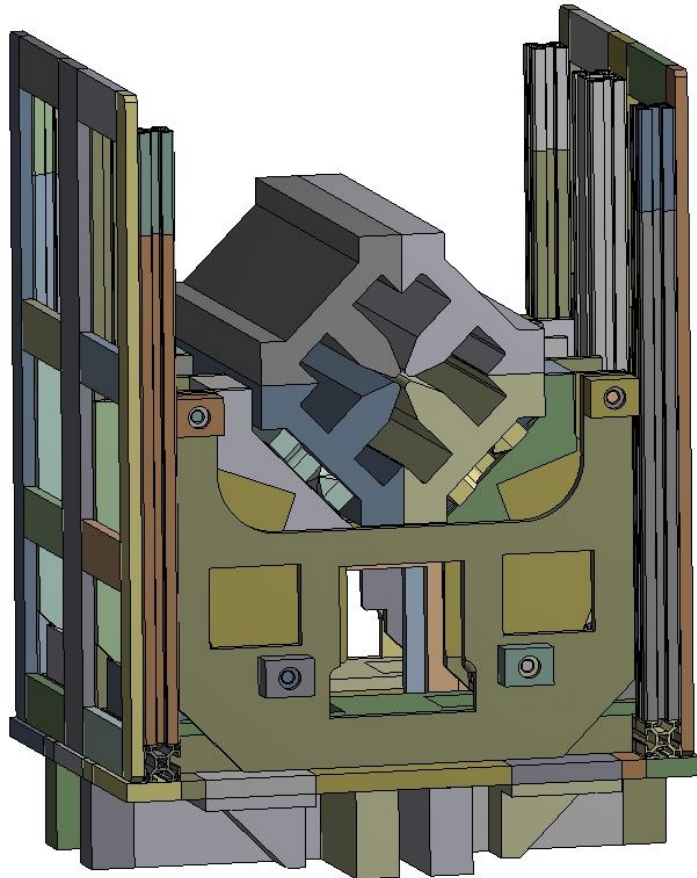
- $P_3 \geq 100 \text{ Hz}$
- $P_2 \cong 15 \mu\text{m}$
- $P_1 \leq 250 \text{ MPa}$

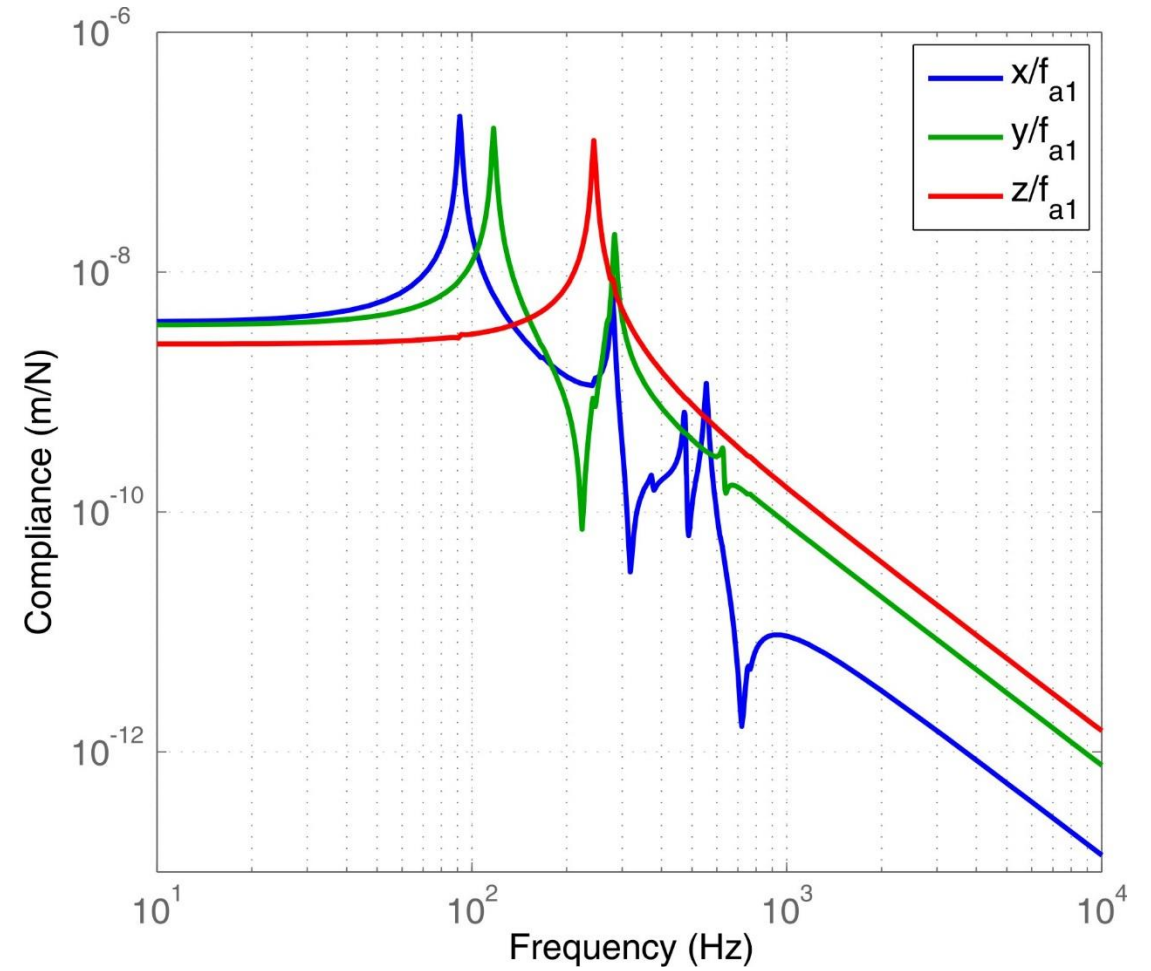
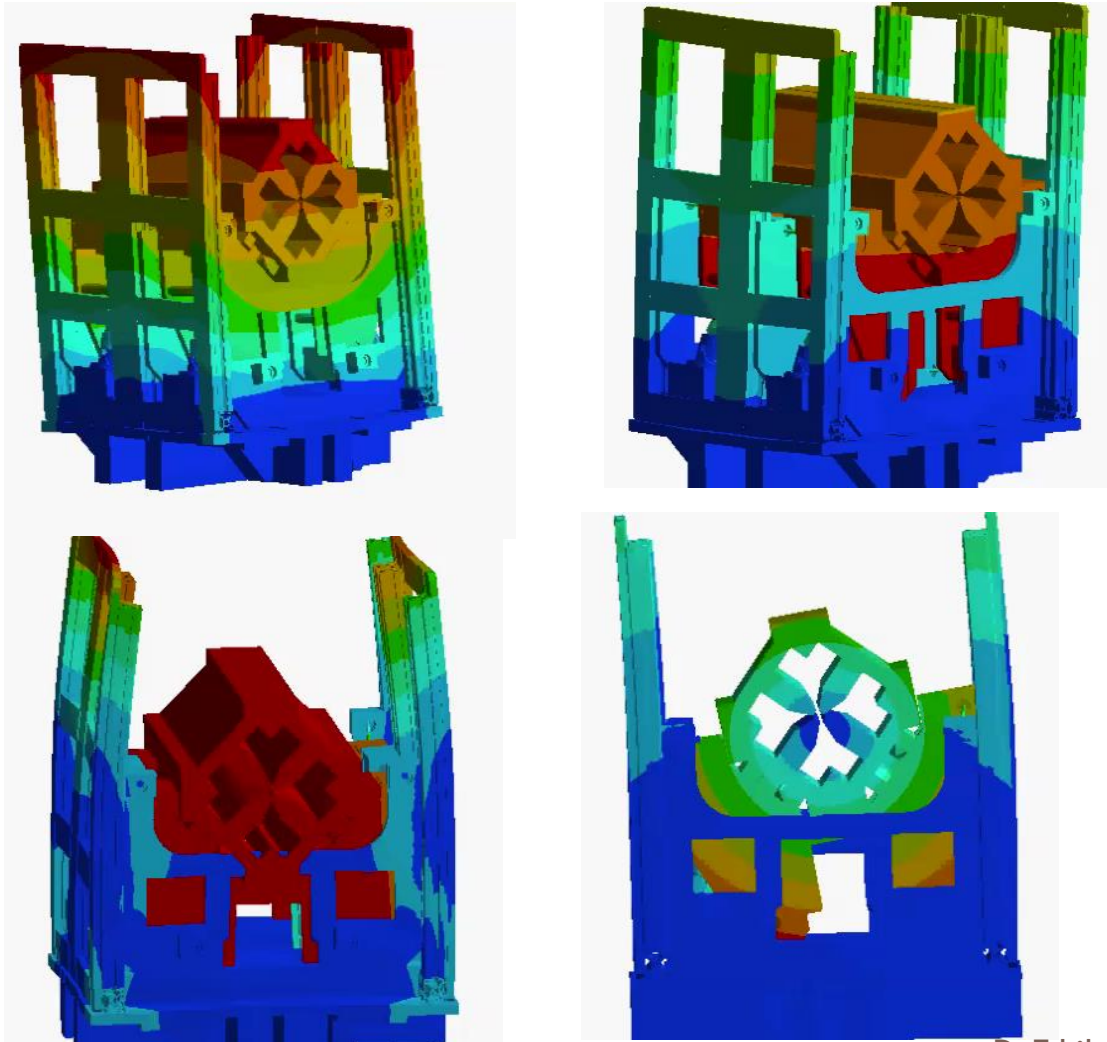
Candidate point		Control parameters	
Notch hinges thickness (P4)	1.21 mm	Vertical magnet displacement (P8)	34 nm
Pillars diameter (P5)	14.58 mm	First eigen frequency (P3)	101 Hz
Pillars fillet radius (P6)	5.81 mm	Remote magnet displacement (P2)	15.7 μm
Notch hinges depth (P7)	51.4 mm	Max equivalent stress (P1)	26 MPa

- Static stiffness of 300 N/ μm !
- Optimization problem statements for other studies possible (e.g. max P3 with P8=25 nm)



FEM-based State space model generation



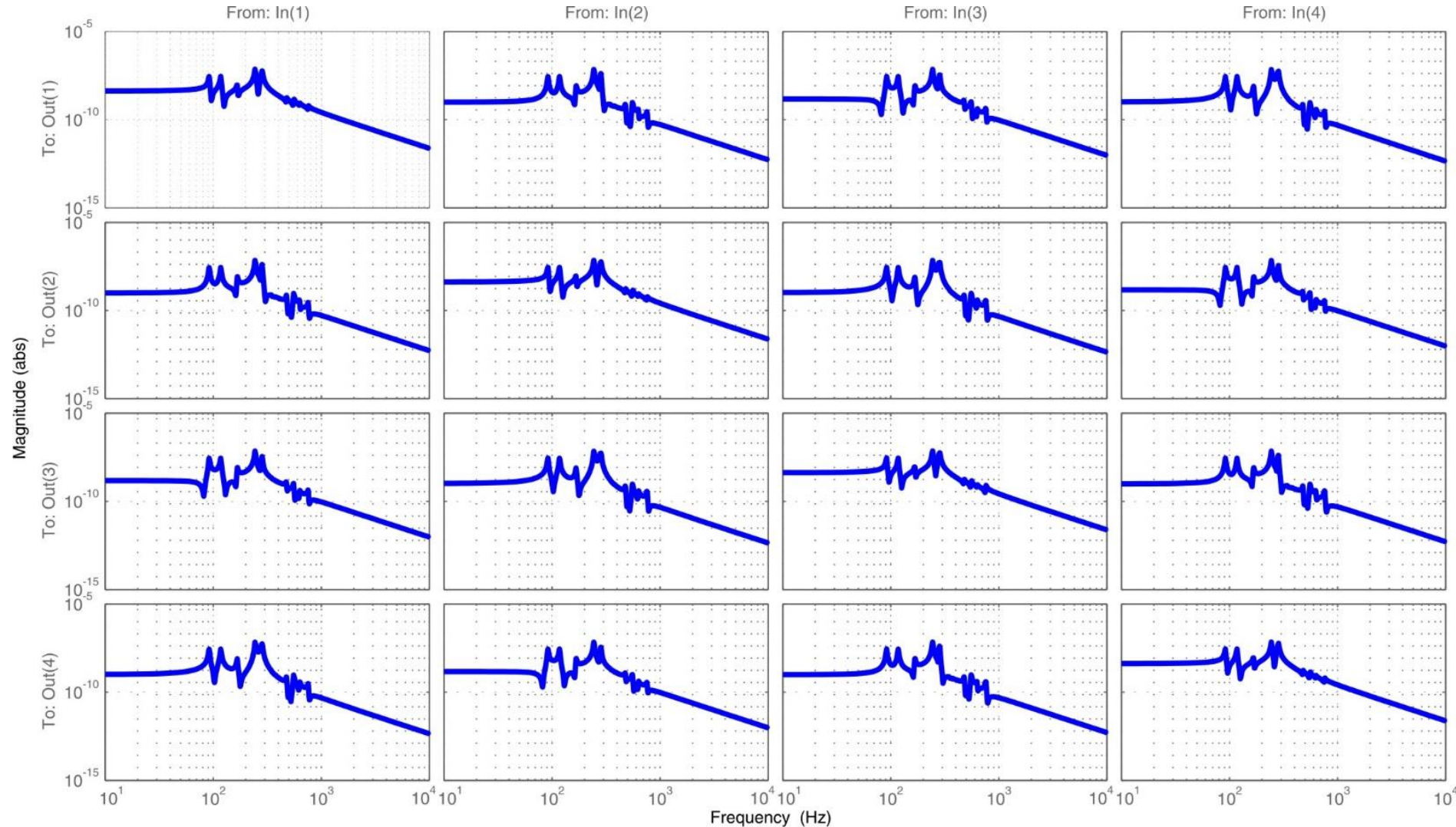


19 Coupled inputs and Outputs

- In(1): front left leg
- In(2): front right leg
- In(3): back left leg
- In(4): back right leg

- Out(1): front lateral encoder
- Out(2): front vertical encoder
- Out(3): back lateral encoder
- Out(4): back vertical encoder

- Interactive MIMO system $G(s)$
 - ➡ Controller design of $C(s)$
 - ➡ Improve reference tracking
 - ➡ Decrease I/O interaction



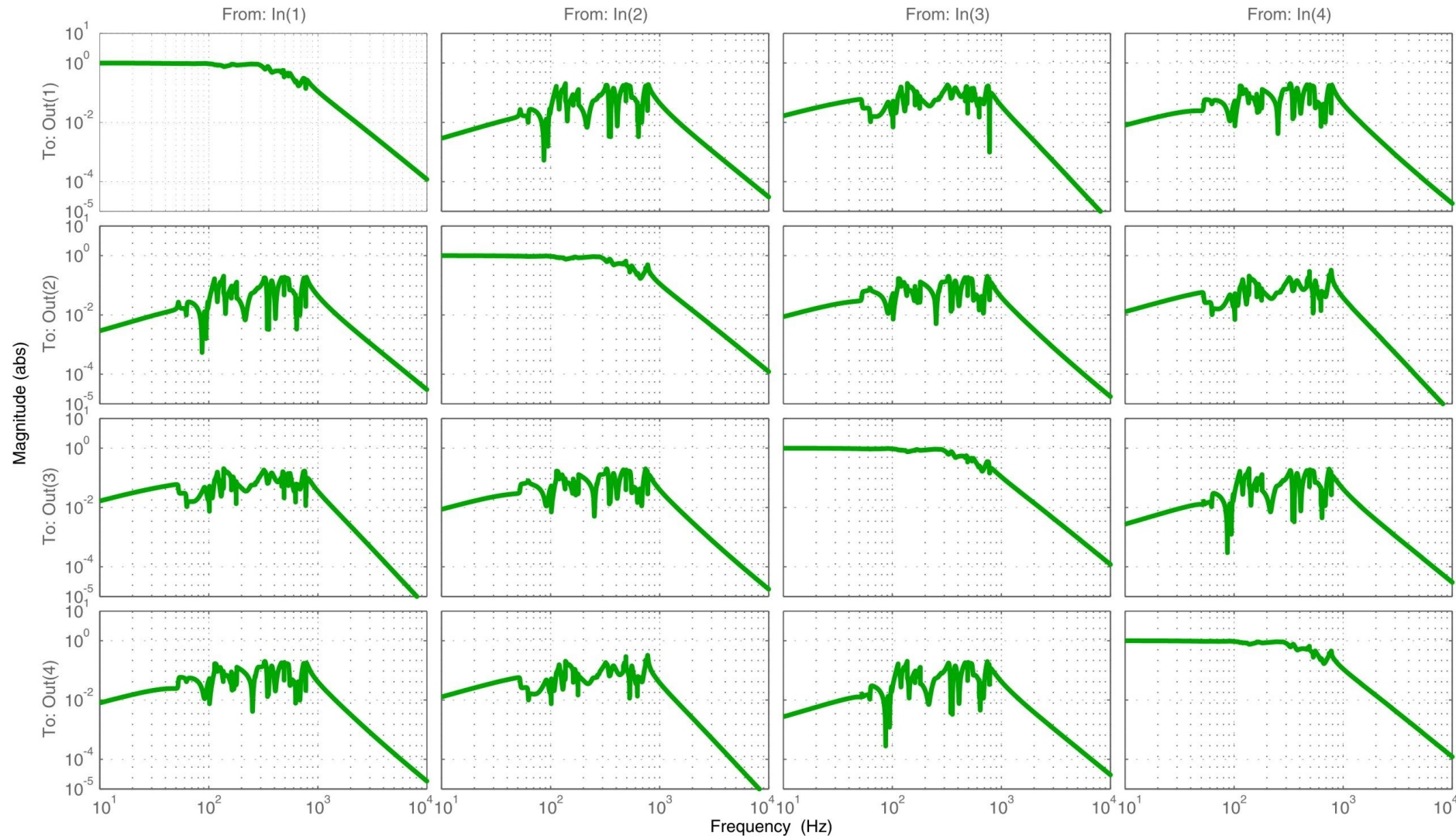
20 Closed loop reference tracking

- In(1): reference signal 1
- In(2): reference signal 2
- In(3): reference signal 3
- In(4): reference signal 4

- Out(1): front lateral encoder
- Out(2): front vertical encoder
- Out(3): back lateral encoder
- Out(4): back vertical encoder

- SVD-controller
- MIMO system $G_{cl}(s)$

$$G_{cl}(s) = \frac{C(s)G(s)}{I(s)+C(s)G(s)}$$



Tools and technique to :

- Evaluate analytically the static stiffness and eigen modes of a compliant mechanism in several dofs
- Perform automatized sensitivity and optimization studies of any CAD assembly
- Generate reduced MIMO state space model based on the FEM of any CAD assembly

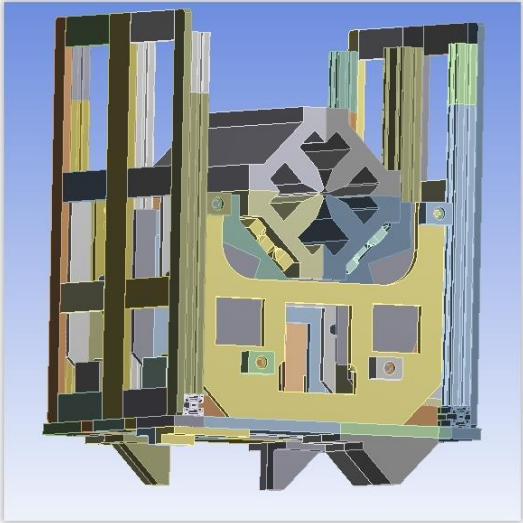
Next steps:

- Controller design for nano-positioning of type 1 module (Closed loop Vs Open loop)
- Experimental comparative tests of positioning controllers
- Test bench design for proof of concept of long range nano-positioning actuator (mechanical design, FEM-based optimization, controller design, experimental validation)

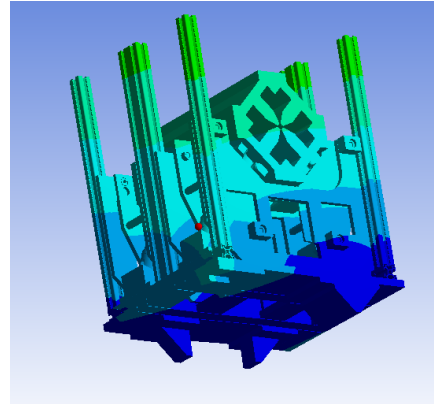


The END

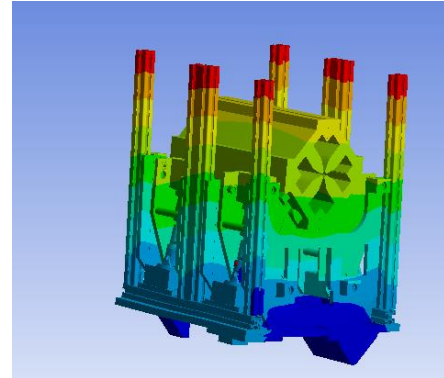
23 Root causes and solution



1. Longitudinal + plate bend



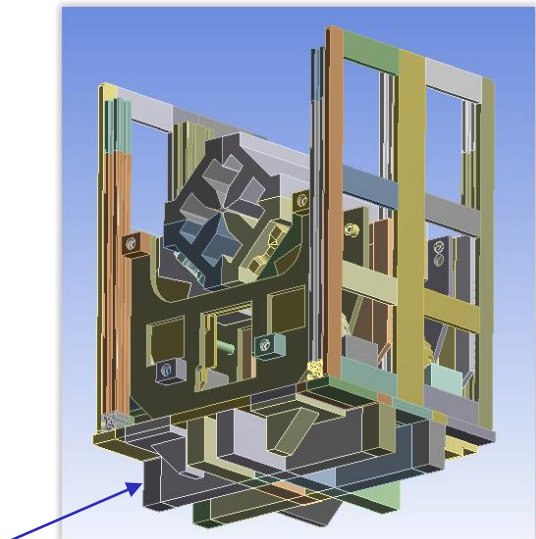
2. side mode + bend



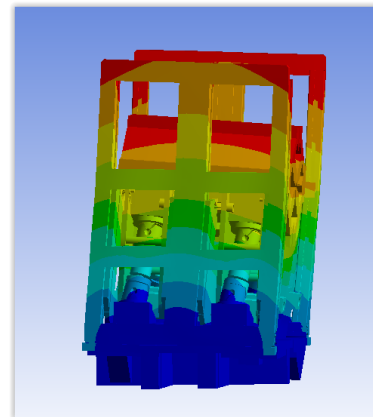
Mode 1: 48.135 Hz
Mode 2: 70.269 Hz
Mode 3: 123.35 Hz

Issues:

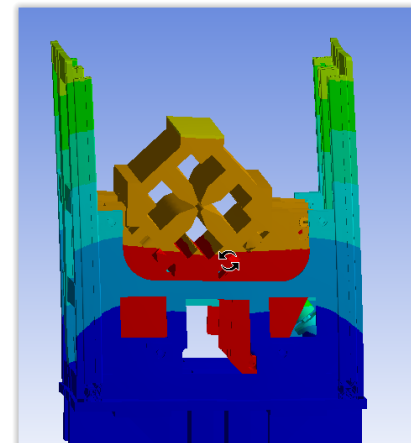
- Non constant support at interface point supported by a manually adjustable jack
- Assembly method of the base plate components
- Base plate stiffness



1. Longitudinal mode



2 Side mode

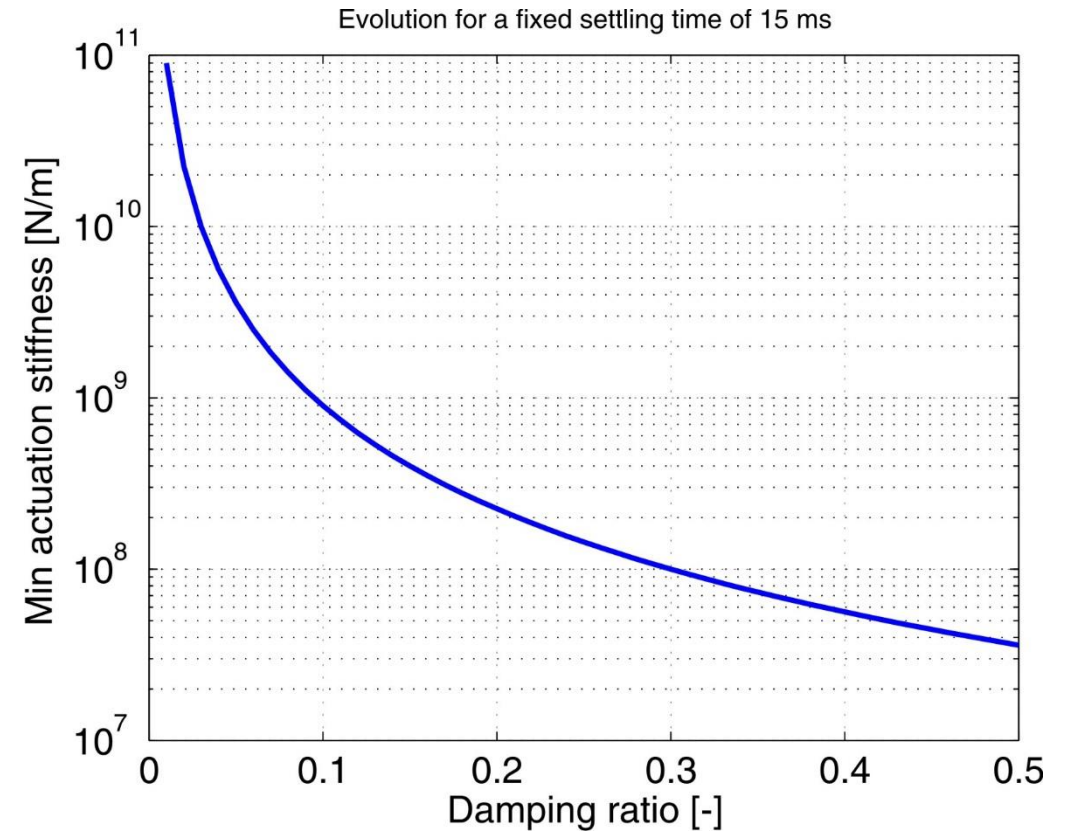
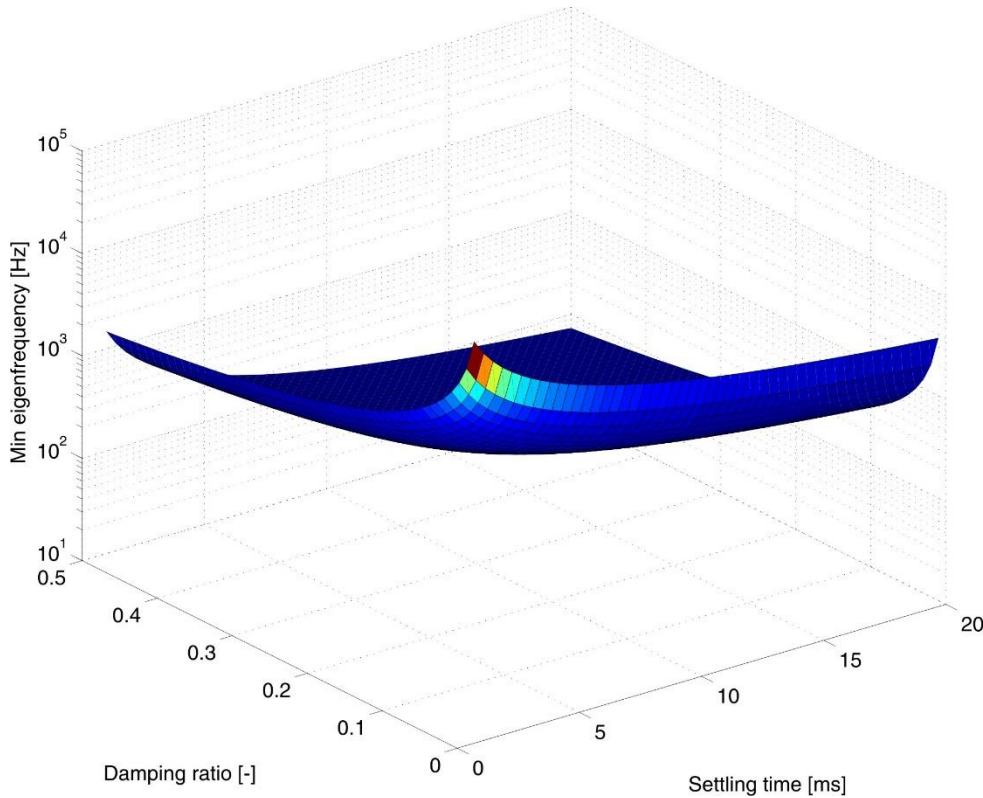


Mode 1: 91.6 Hz
Mode 2: 117.2 Hz
Mode 3: 167.14 Hz

- Larger flat contact surface with ground
- Base plate reinforcement (longitudinal)
- Gluing + bolting base plate components
- Lowest mode in longitudinal direction
➔ Not an issue

➔ Upgraded base plate designed

25 Required stiffness for positioning

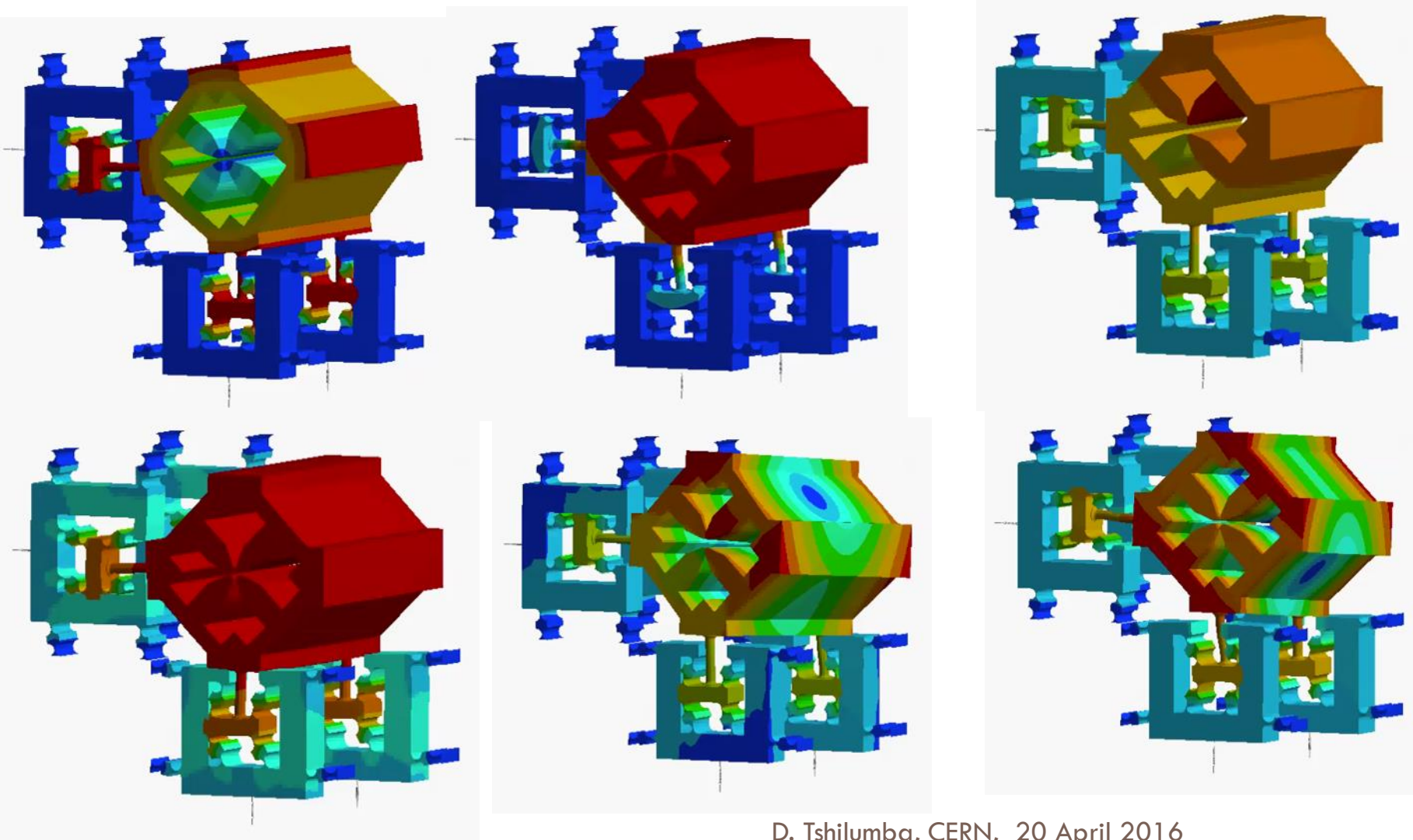


Conclusion: With a settling time $t_s = 15ms$ and a damping ratio $\xi = 0.15$, the required stiffness support is $k_{sup} = 400N/\mu m$ for a positioning step of 50 nm



Required force for nanopositioning: $F_{Inertia} + F_{elastic} = 2N + 20N$

26 Compliance matrix method



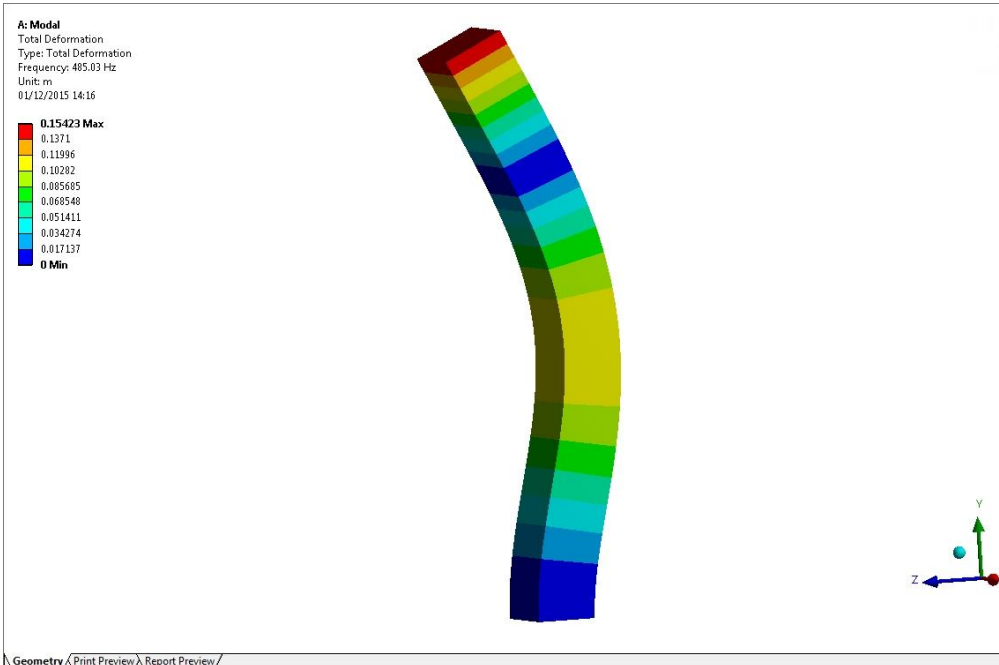
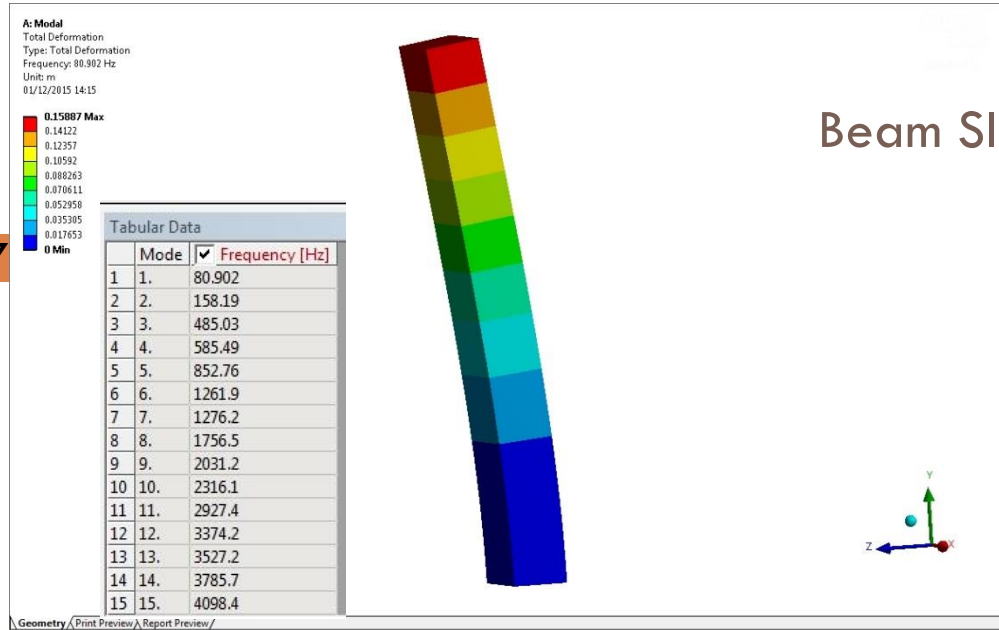
	Analytical	FEA
Mode 1	43 Hz	42 Hz
Mode 2	65 Hz	55 Hz
Mode 3	65 Hz	58 Hz
Mode 4	107 Hz	111 Hz
Mode 5	195 Hz	124 Hz
Mode 6	295 Hz	167 Hz

Beam SISO model

Introduction

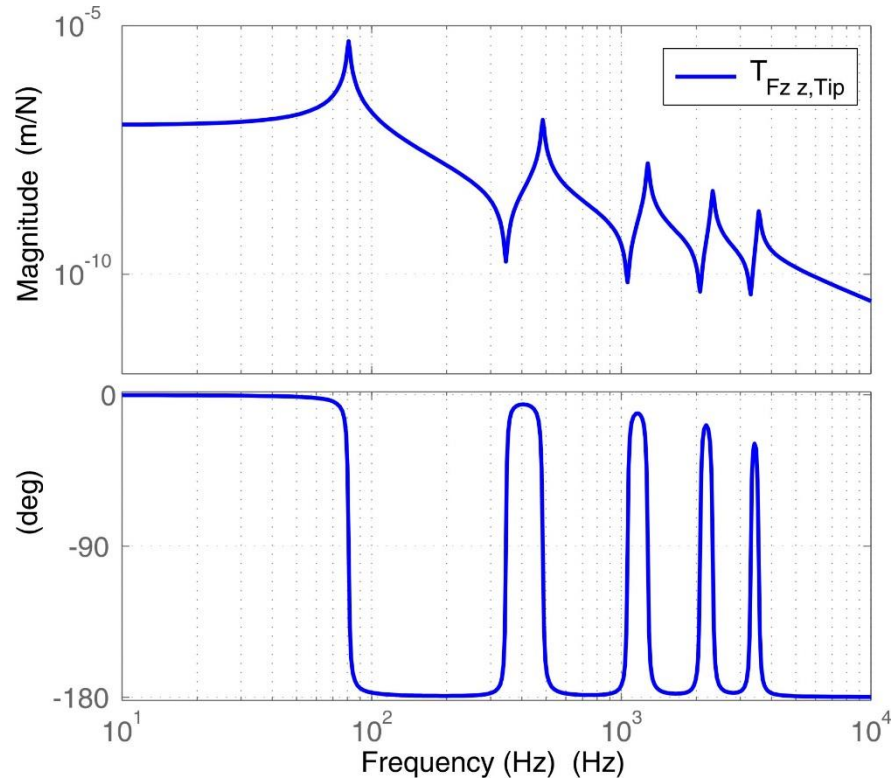
- Beam with Clamped-free boundary conditions
- Transfer functions extraction from FEM (dynamics)
 - Choice in actuators and sensors placement (observability, controllability)
 - Evaluation of response to known excitation spectra
 - Starting point for controller design

27



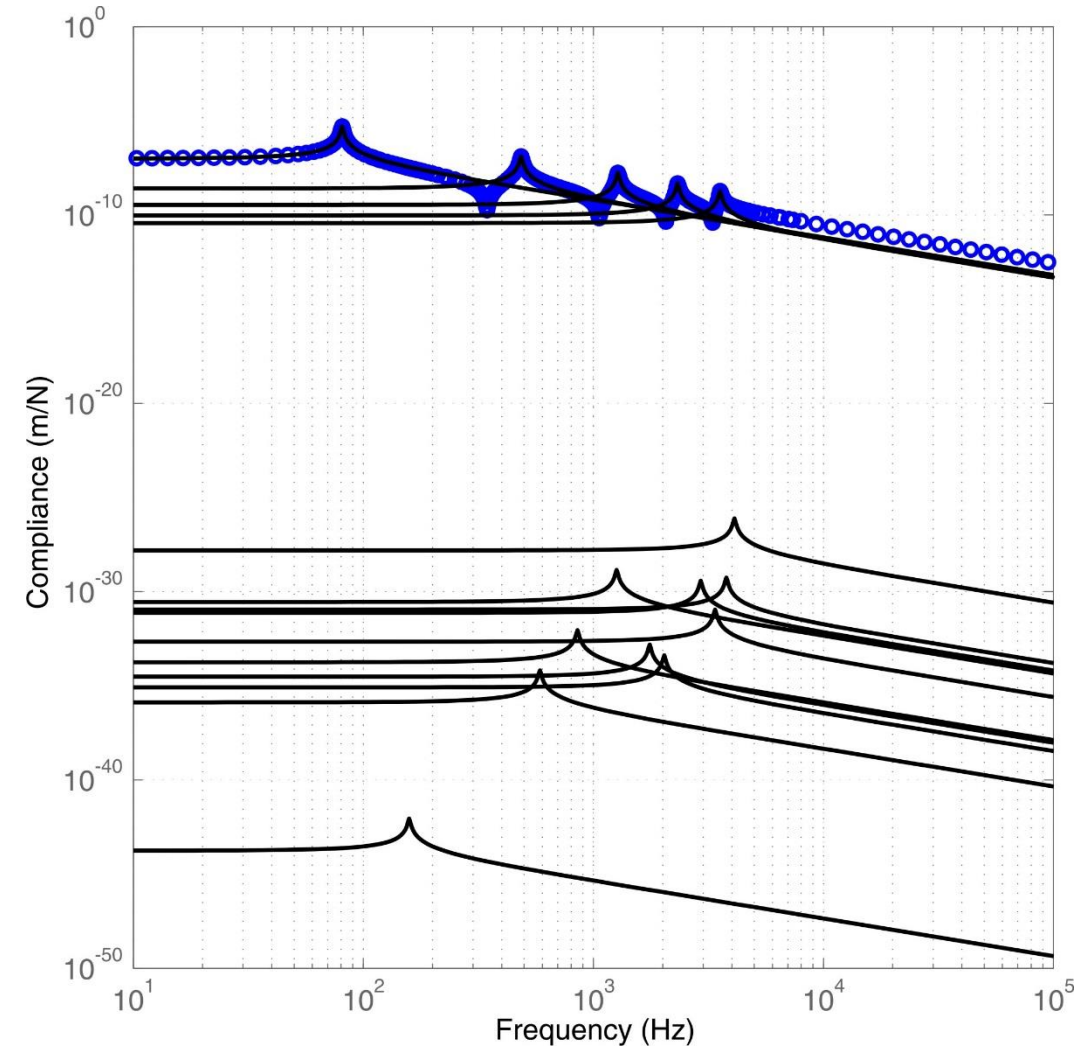
28 Total transfer function and modal contributions

- Beam with Clamped-free boundary conditions
- All the nodes of the FE model retained
- ➔ Modal matrix of the whole FE model constructed
- Choice in input and output dofs (e.g. x, y, z at the tip)



$$\frac{z_j}{F_k} = \sum_{i=1}^m \frac{\phi_{ji}\phi_{ki}}{s^2 + 2\zeta_i\omega_i + \omega_i^2}$$

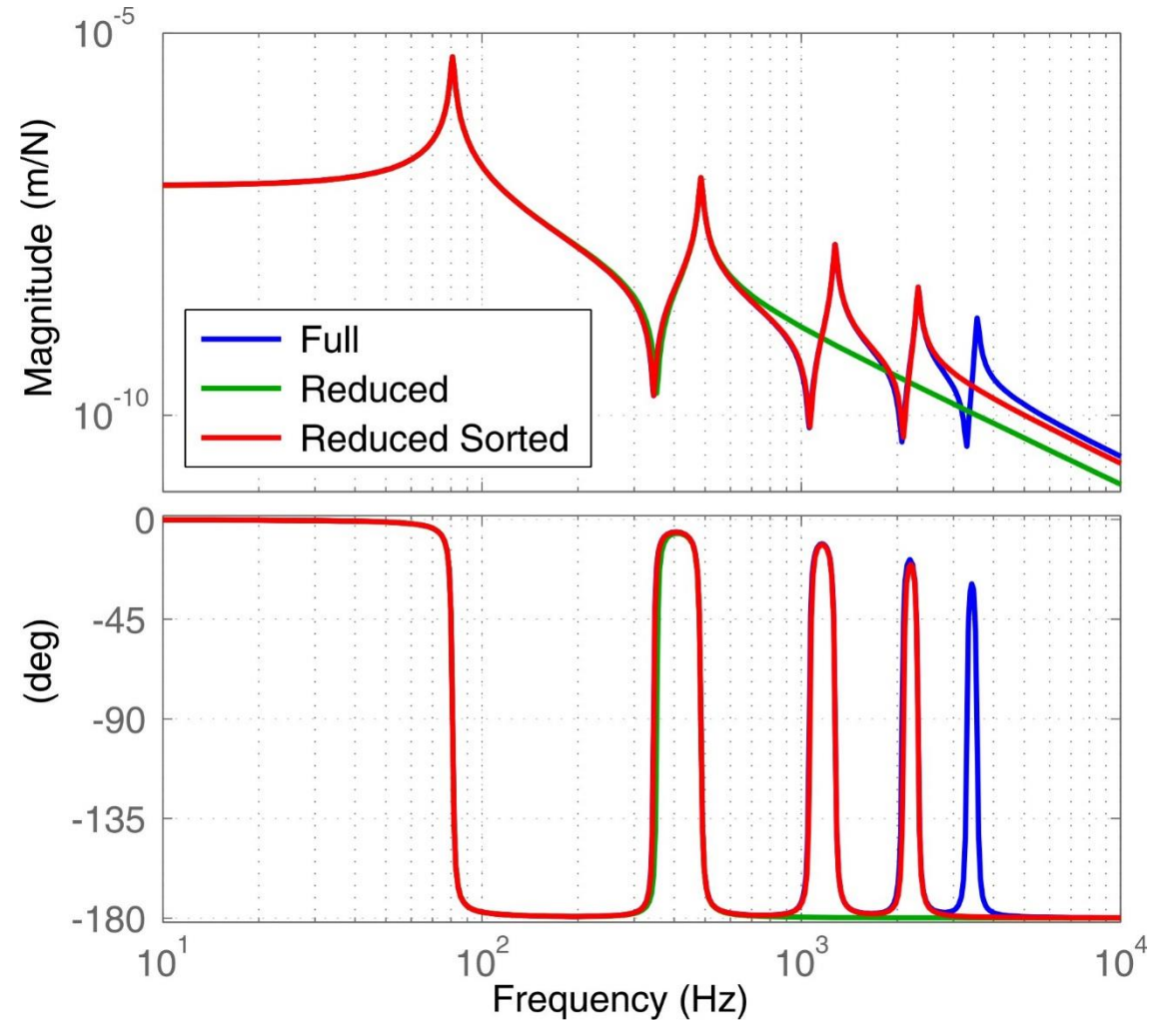
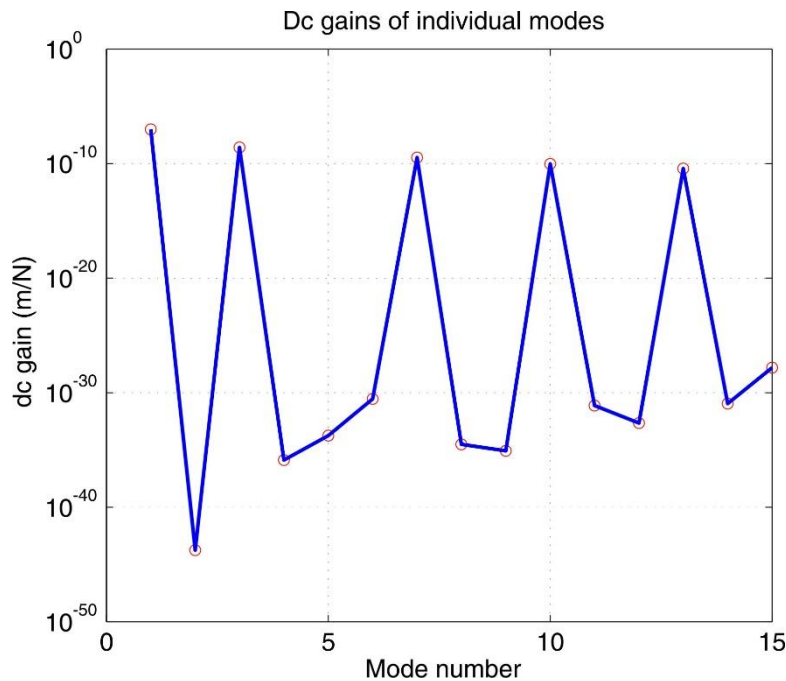
ϕ Mass normalized modal matrix



29 Model order reduction

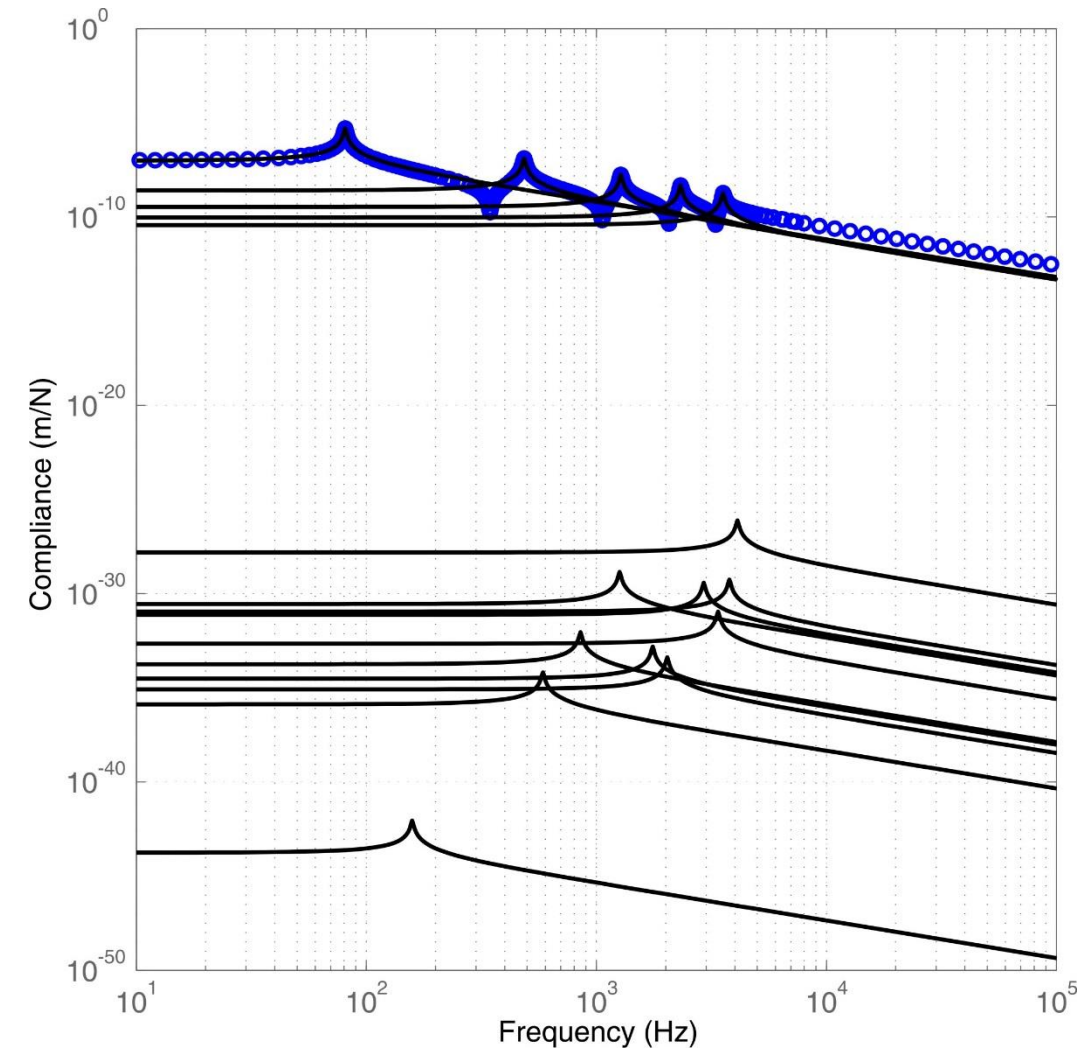
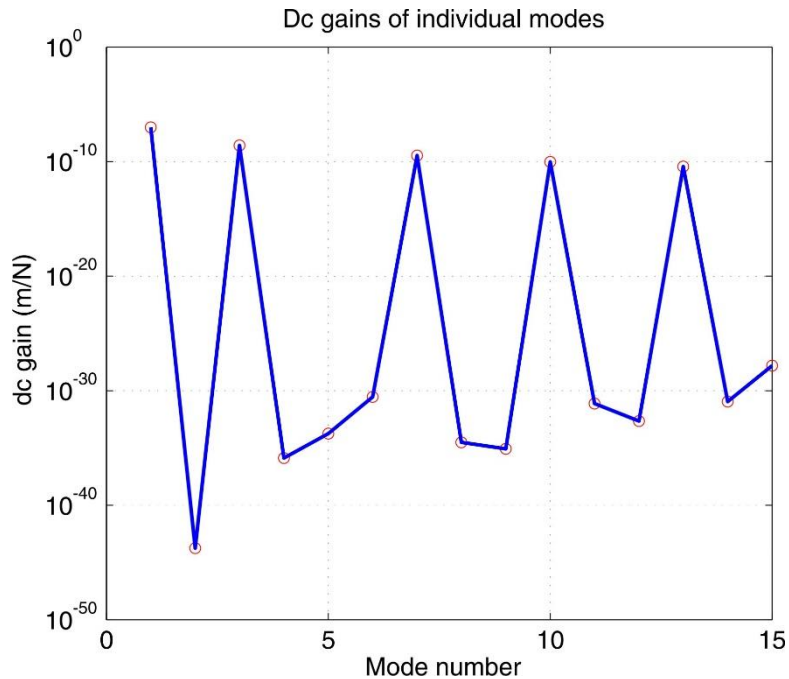
- Reduction of the order of the state space model by keeping the first p modes (e.g. $p = 4$)
- Ranking increases the amount of resonances kept in the reduced model
- Advantage: reduction of the number of poles in the transfer function

Controller design simplified



30 Modes ranking by dc gains

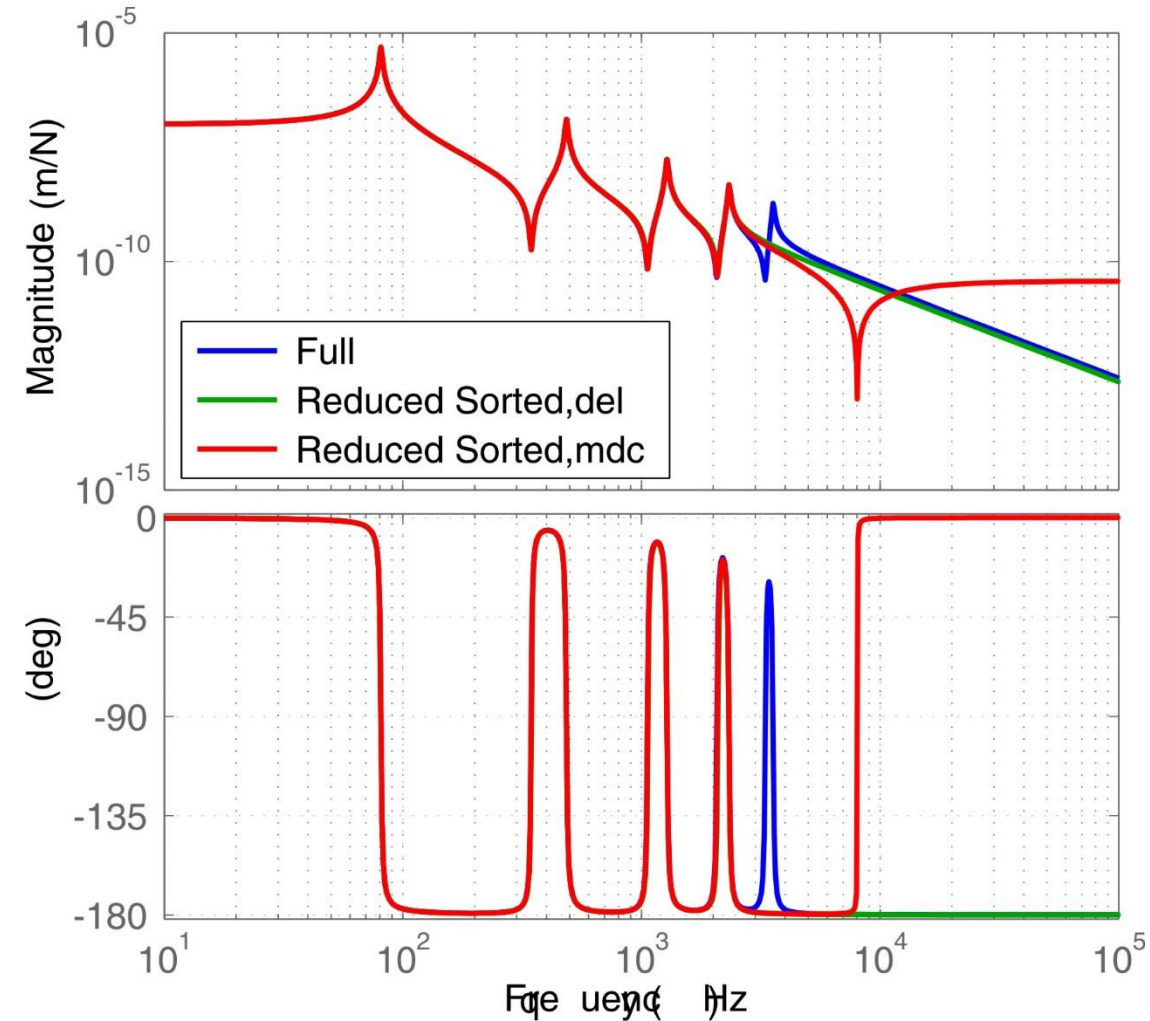
- Ranking of the modes by decreasing order of dc gains in state space model
- Sorting has an influence for the reduction of the state space model
- Dc gain value for mode i : $dc_i = \frac{\phi_{ji}\phi_{ki}}{\omega_i^2}$
- Modes 1, 3, 7, 10 and 13 have the highest dc gains

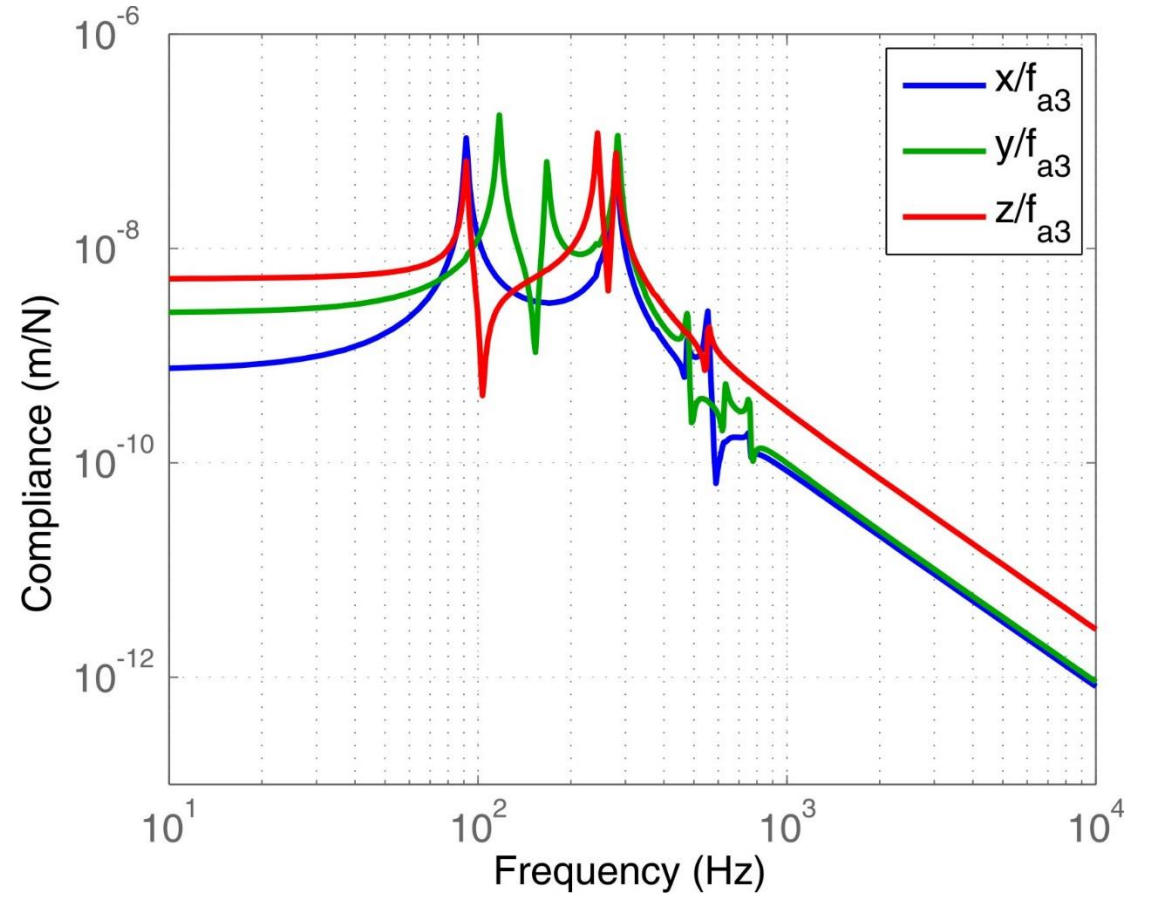
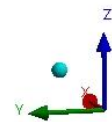
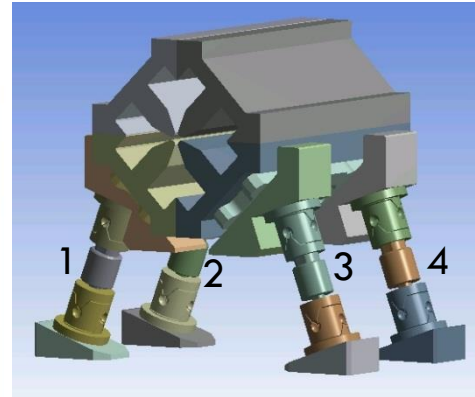
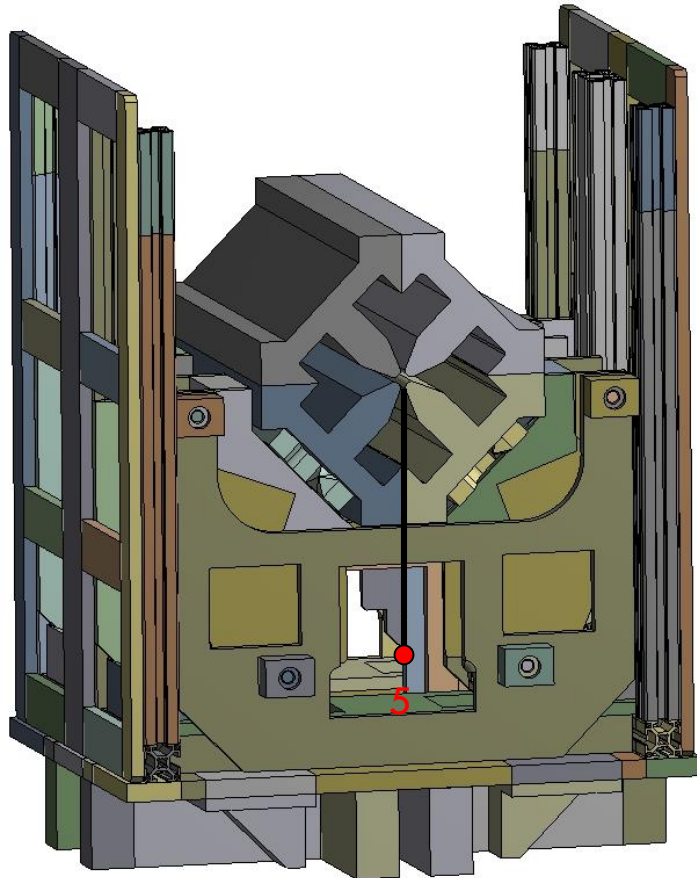


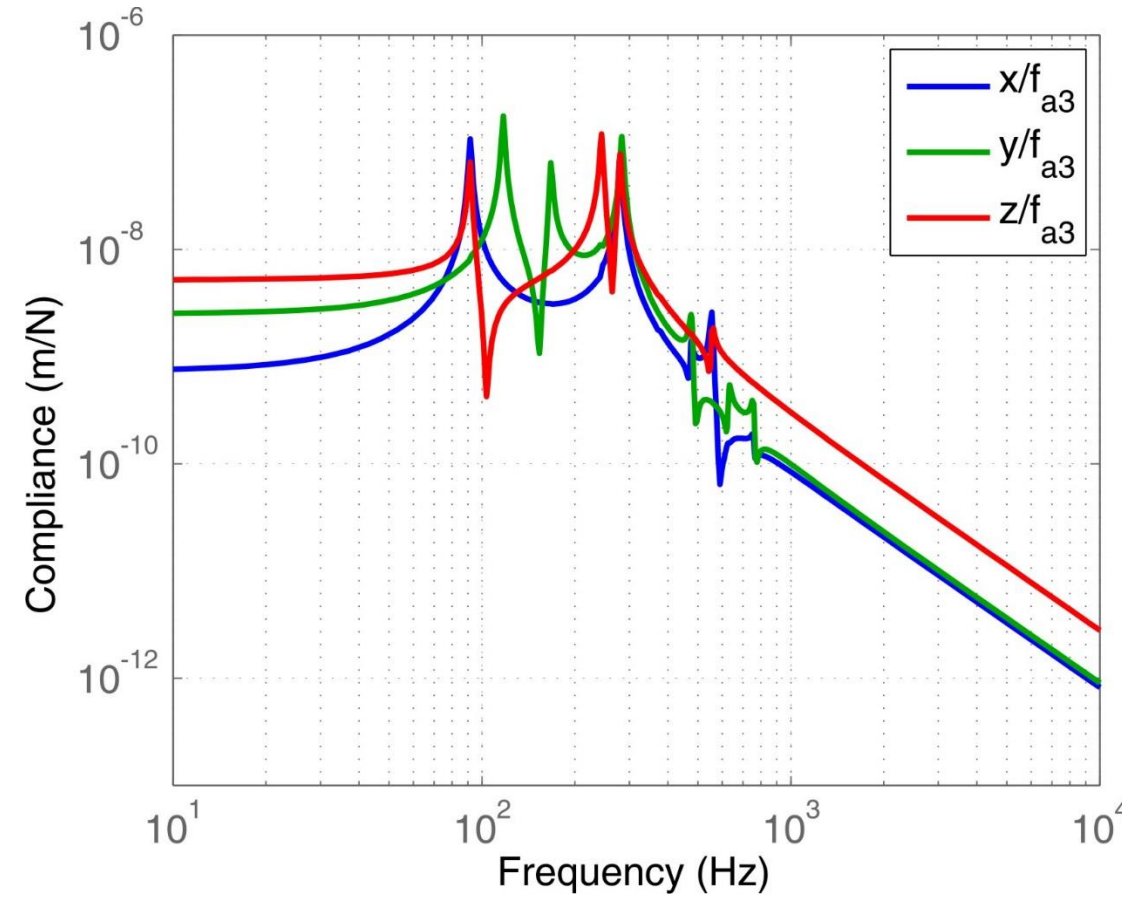
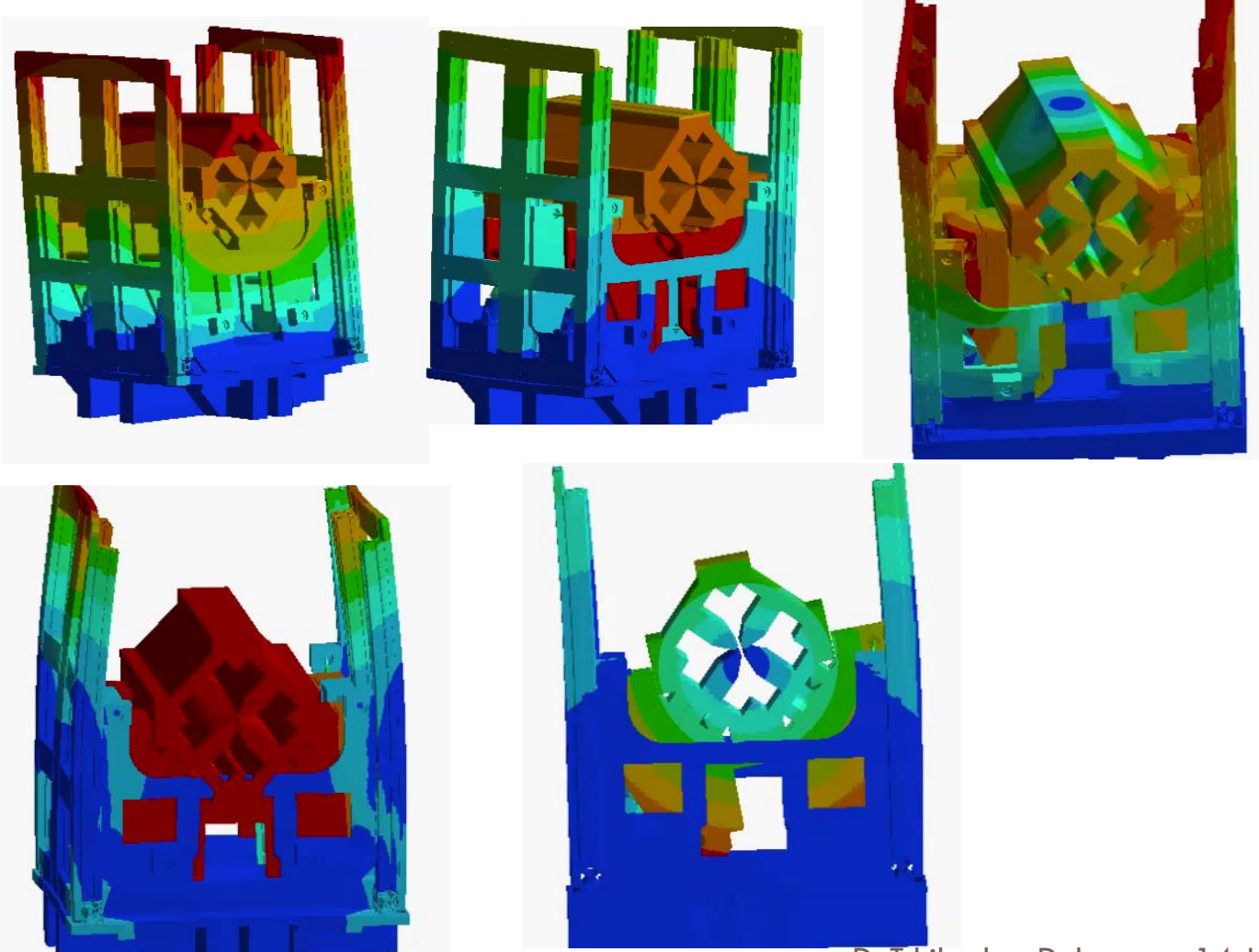
31 Model reduction

- ❑ Comparison between « matched dc gain » technique and « suppression » technique
- ❑ Reduction of the order of the state space model by keeping the first p modes (e.g. $p = 4$)
- ❑ Superelement method uses matched dc gain reduction

Matched dc gain	suppression
<ul style="list-style-type: none"> • The eliminated modes are condensed with a transformation matrix T $x_r = Tx = T \begin{bmatrix} x_r \\ x_e \end{bmatrix}$ • Exact dc gain guaranteed ➔ dc gain ranking not required • Constant amplitude at high frequency due to constant term in the direct transmission matrix D_{red} of the reduced state space model 	<ul style="list-style-type: none"> • The eliminated modes are simply suppressed ➔ dc gain ranking required • High frequency decreasing behaviour is conserved

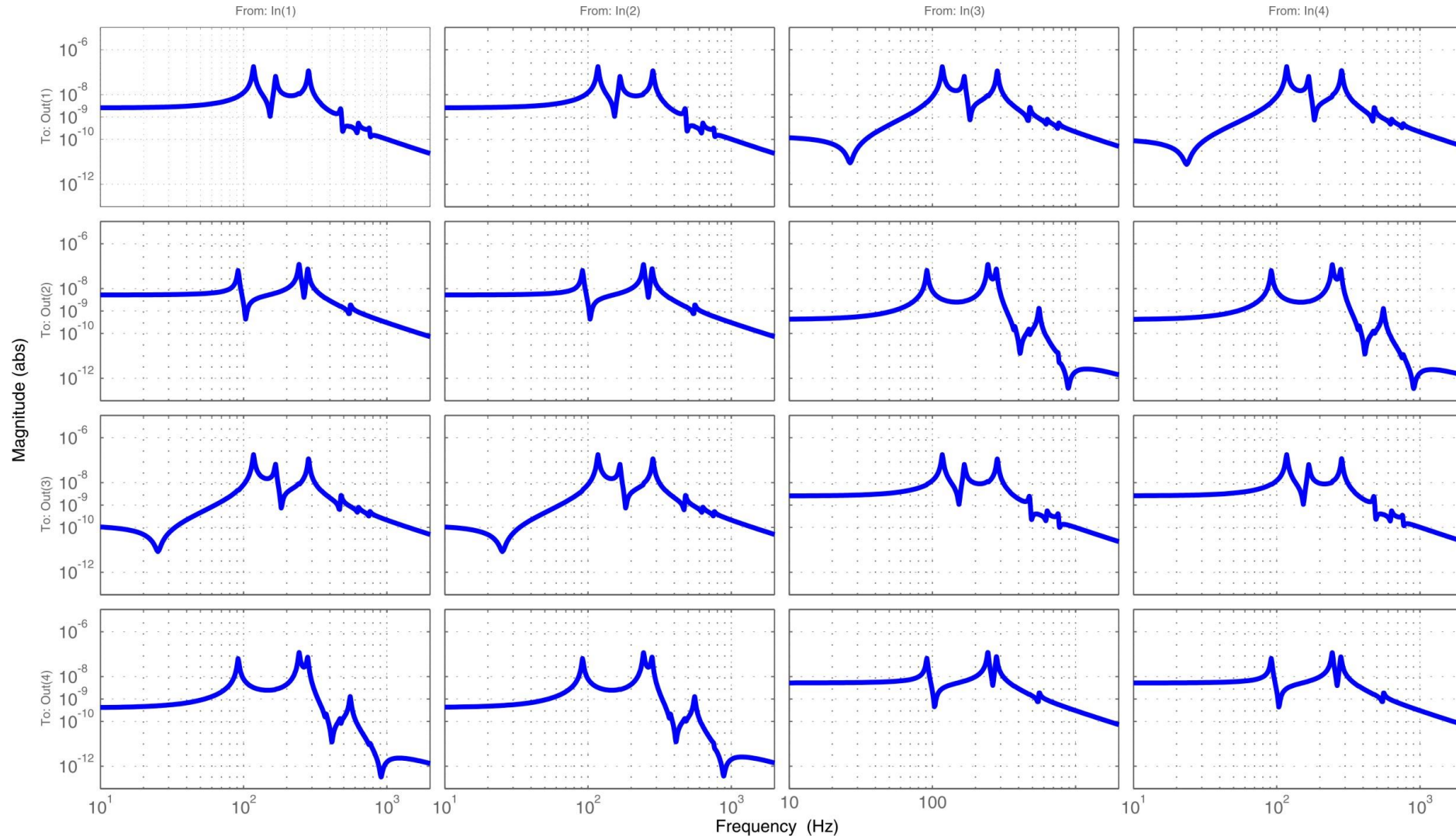






34 Coupled inputs and Outputs

- In(1): front left leg
 - In(2): front right leg
 - In(3): back left leg
 - In(4): back right leg
-
- Out(1): front lateral encoder
 - Out(2): front vertical encoder
 - Out(3): back lateral encoder
 - Out(4): back vertical encoder
-
- Interactive MIMO system $G(s)$
 - ➡ Controller design of $C(s)$
 - ➡ Improve reference tracking
 - ➡ Decrease I/O interaction



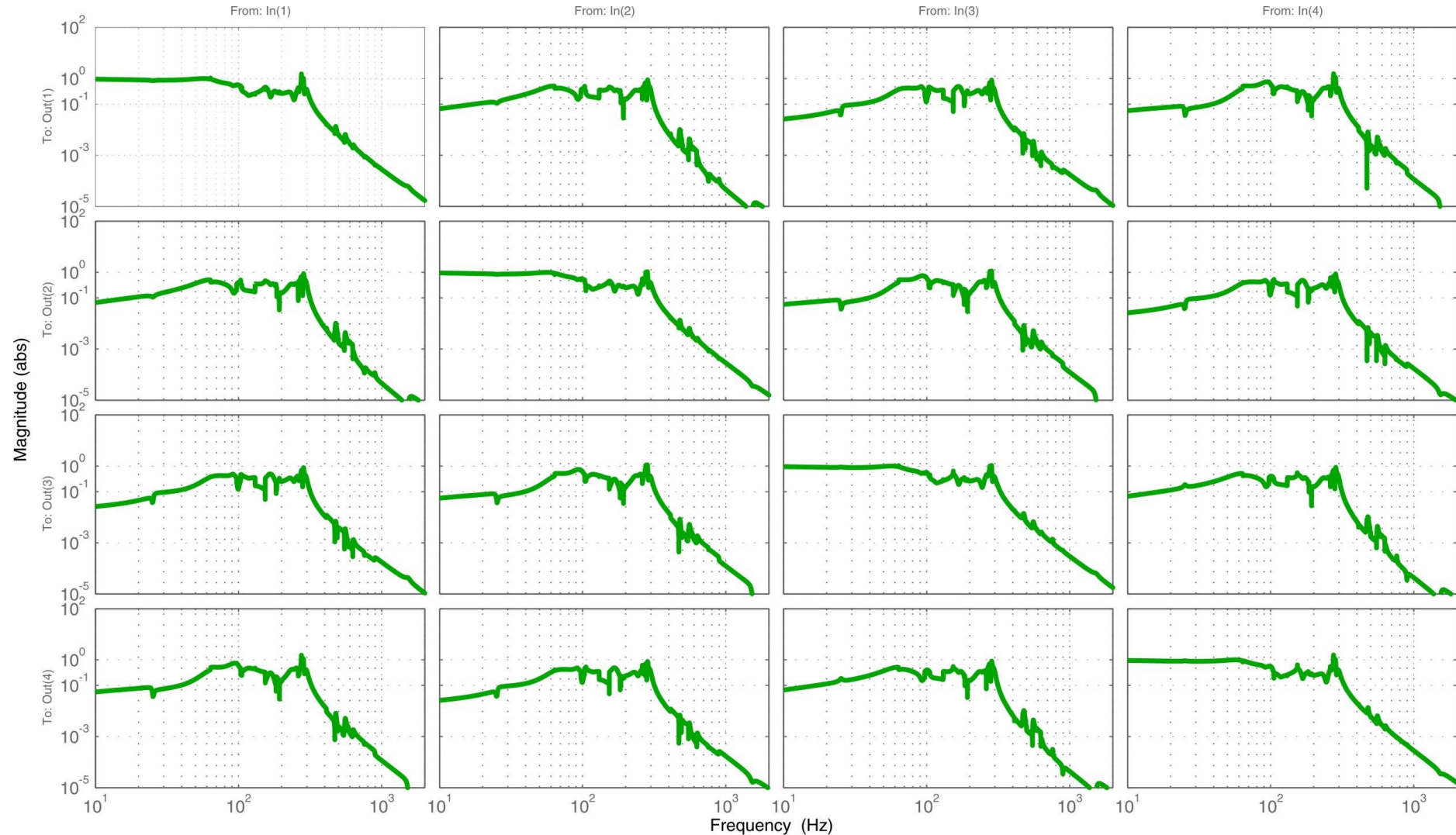
35 Closed loop reference tracking

- In(1): reference signal 1
- In(2): reference signal 2
- In(3): reference signal 3
- In(4): reference signal 4

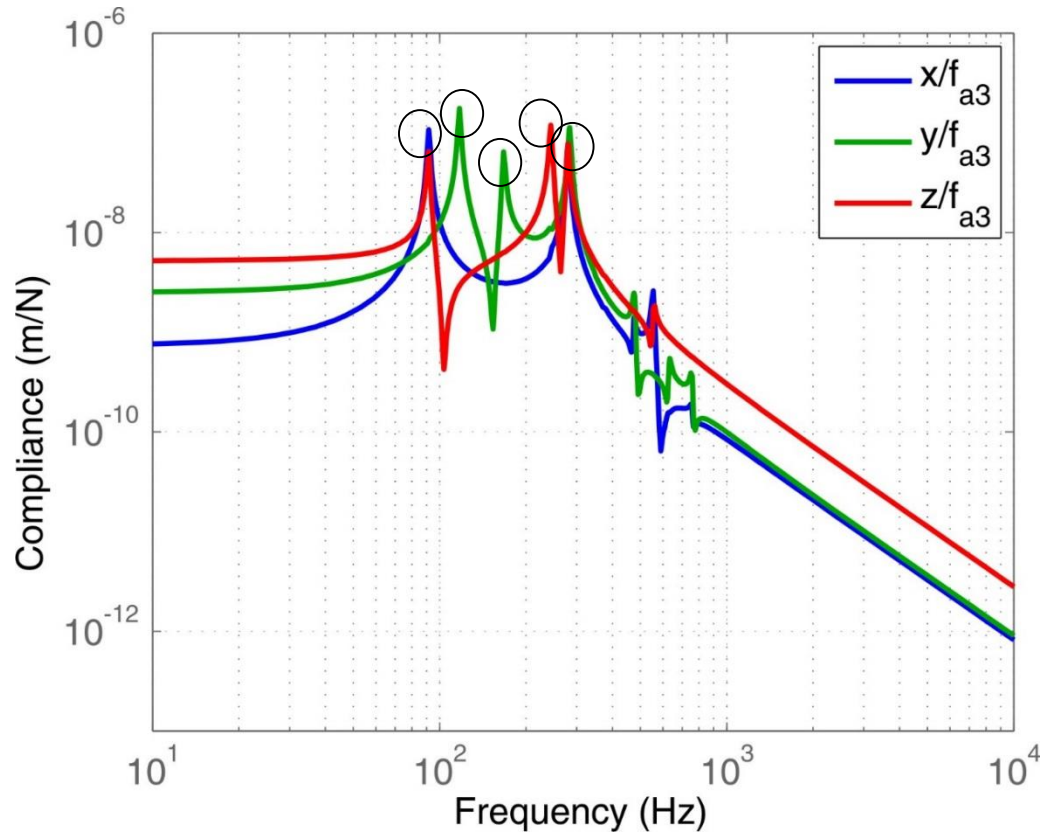
- Out(1): front lateral encoder
- Out(2): front vertical encoder
- Out(3): back lateral encoder
- Out(4): back vertical encoder

- SVD-controller
- MIMO system $G_{cl}(s)$

$$G_{cl}(s) = \frac{C(s)G(s)}{I(s)+C(s)G(s)}$$

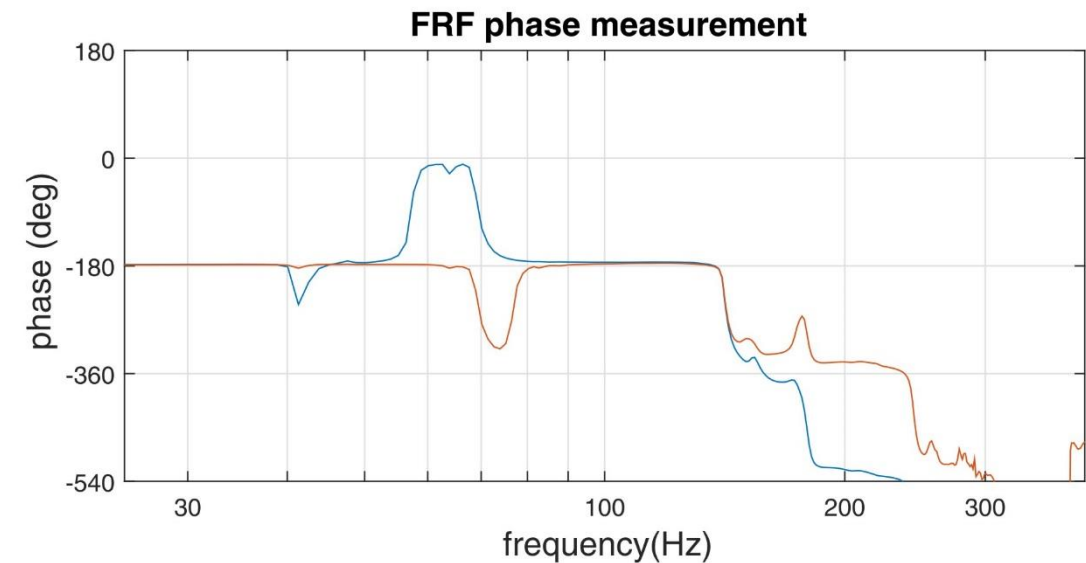
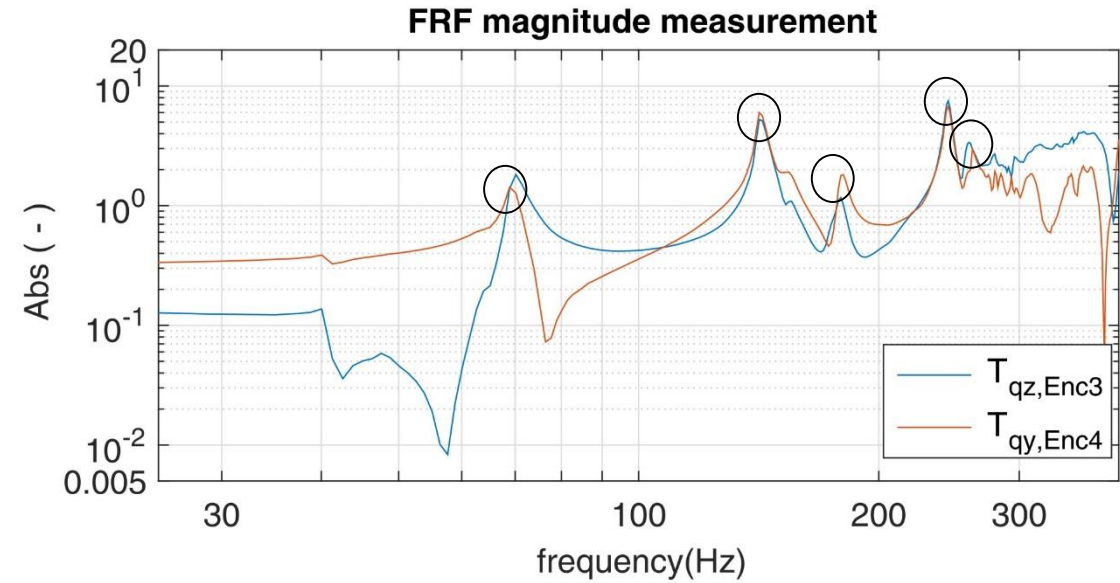


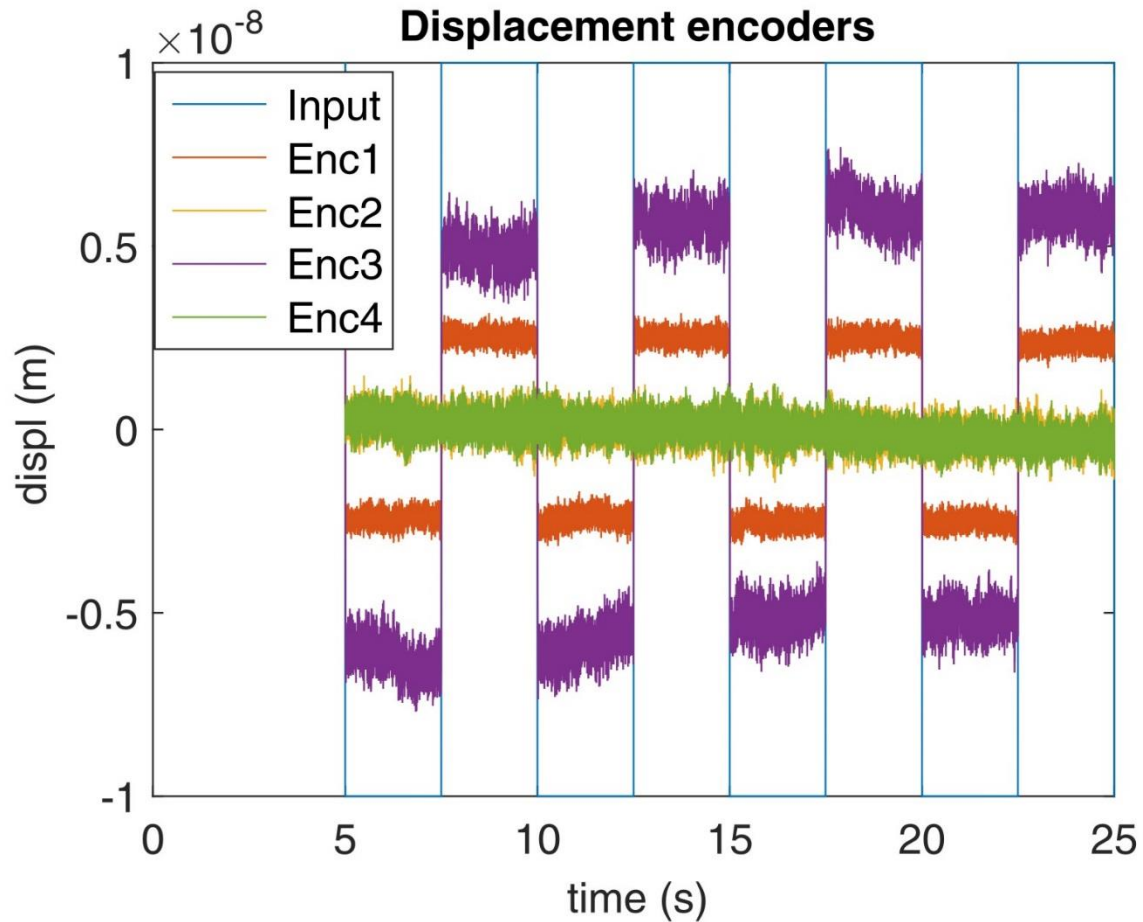
36 Model validation



- Coupling in measured modes
- Parasitic mode at 40 Hz (mode 1)
- Measured modes 2 and 3 shifted

Potential causes : unglued reinforcement beam , distorted elements

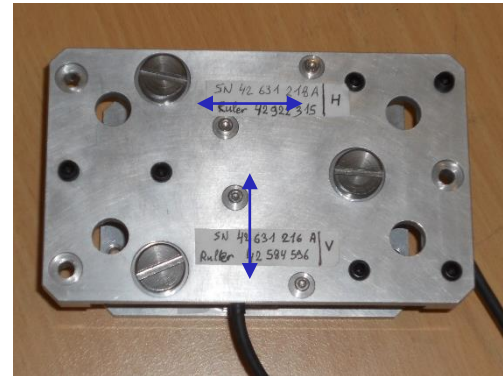
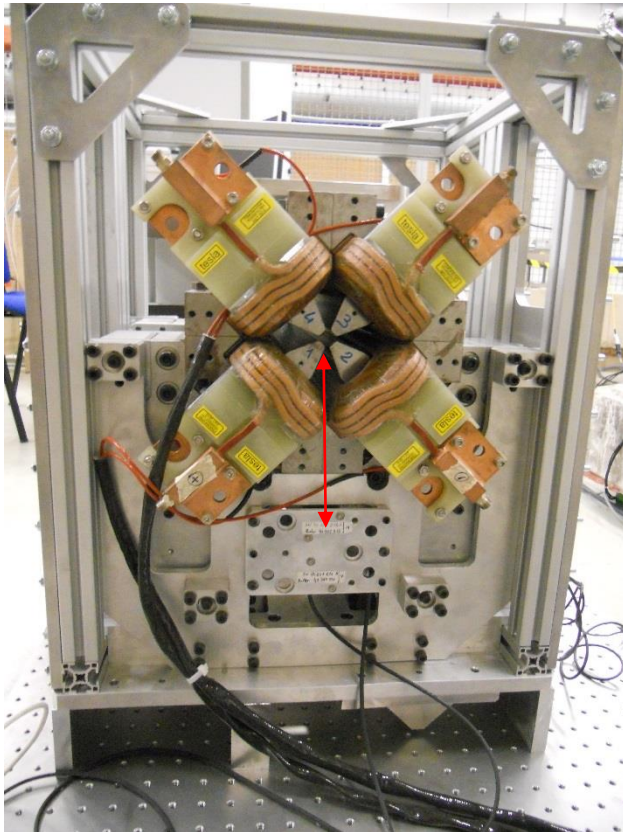




- Nominal displacement : 10 nm
- PI controllers ON
- Max Encoder1 readout : 2.5 nm
- Max Encoder3 readout : 5 nm
- Closed loop noise : 2nm
- Settling time :
 - 30 ms (Encoder 3)
 - 30 ms (Encoder 2)

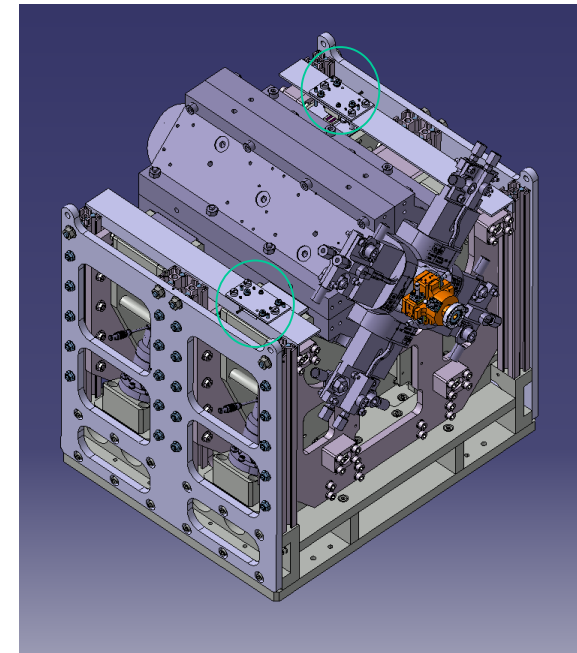
Noise generated by strain gauge in closed loop

Measurement on Type 1 module: Preliminary tests

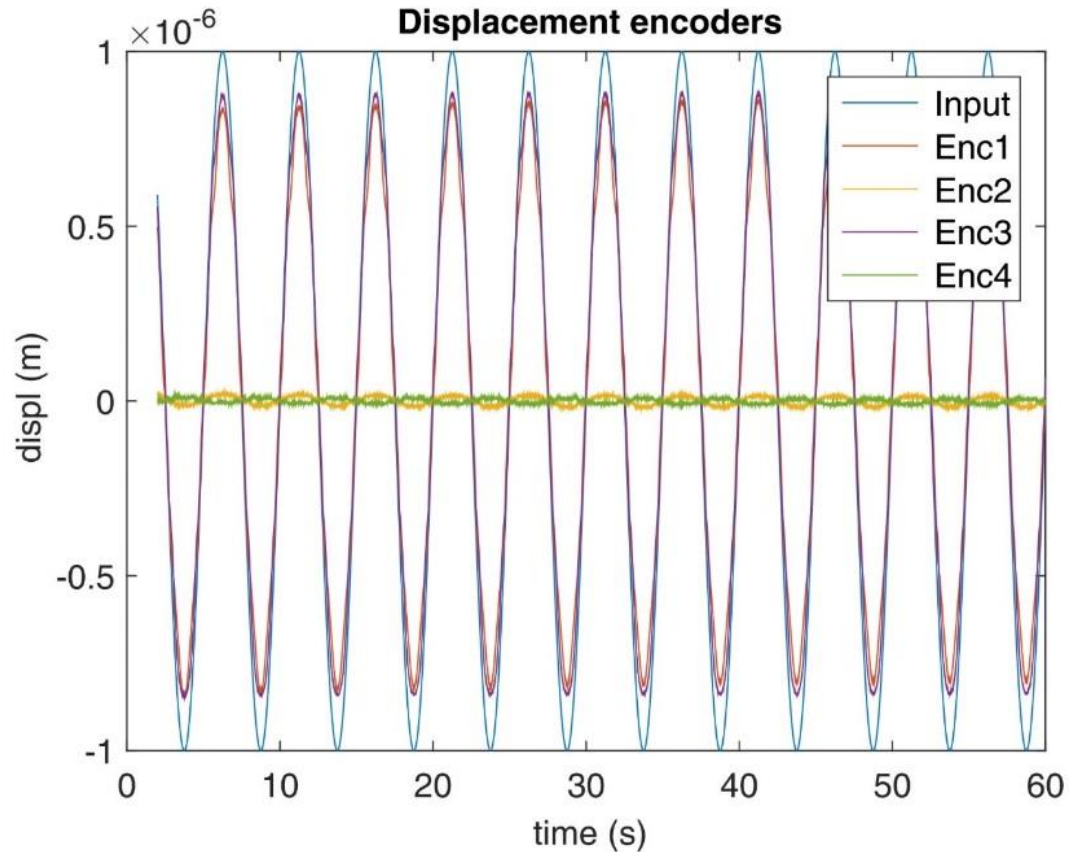


- PI Piezo stacks P225
- Integrated strain gauges
- Heidenhain LIP 281 linear encoders
- Offseted lateral encoders

➔ Upgrade foreseen



40 Vertical displacement

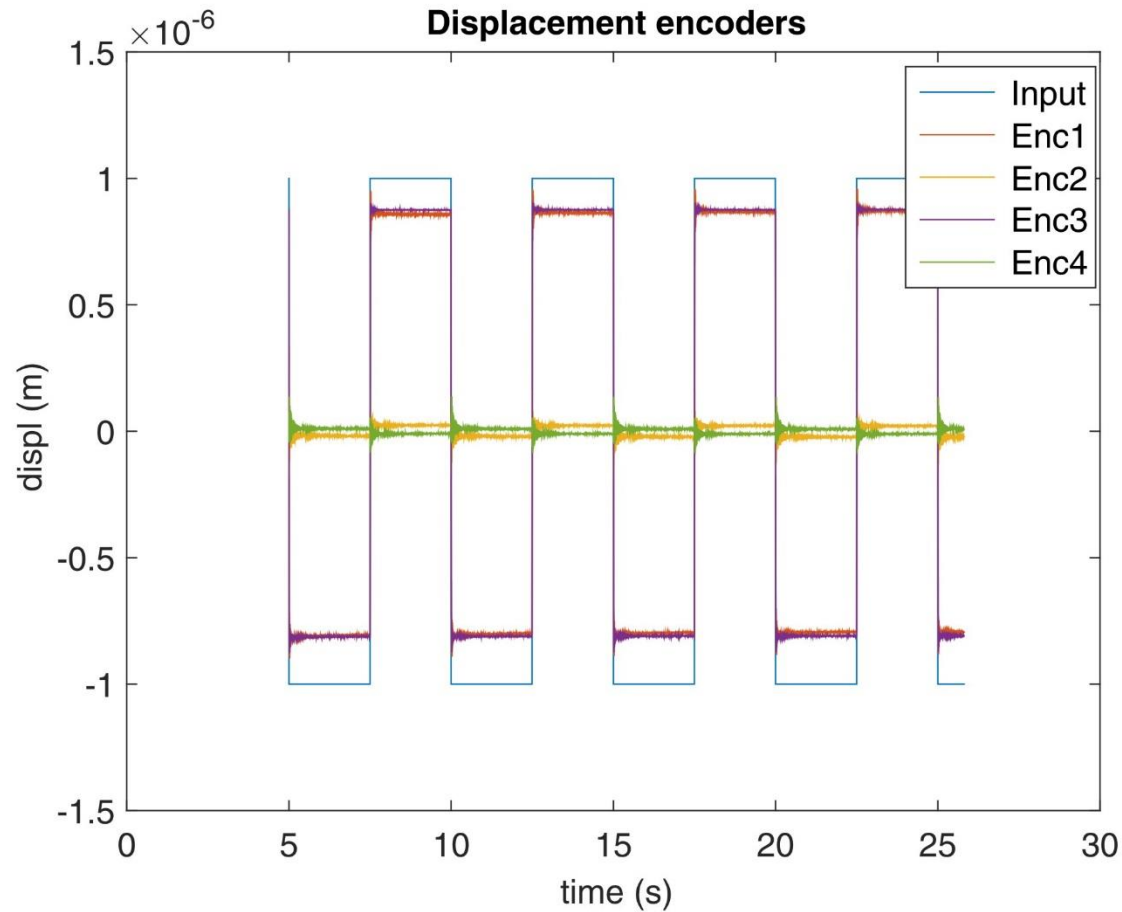


Objective: compensate imperfections from manufacturing and assembly process

- Nominal displacement : 1 μm
- PI controllers ON
- Max Encoder1 readout : 853 nm
- Max Encoder3 readout : 863 nm
- Max lateral encoder readout : 20 nm ($\sim 2\%$)

- DC offsets PZTs:
 - 3.2463 V (PZT 573)
 - 4.8298 V (PZT 575)
 - 4.1442 V (PZT 572)
 - 3.5819 V (PZT 574)

41 Vertical displacement



- Nominal displacement : 1 μ m
- PI controllers ON
- Max Encoder1 readout : 866 nm
- Max Encoder3 readout : 876 nm
- Max lateral encoder readout : 20 nm (~2%)

- Closed loop noise: 2 nm (strain gauges)

- Further tests required
 - Linearity assessment
 - Repeatability assessment
 - Encoder based active positioning

42 Model validation

Mode	Direction	Frequency (model)
1	longitudinal	91 Hz
2	lateral	117 Hz
3	yaw	167 Hz
4	vertical	244 Hz
5	roll	270 Hz

Mode	Frequency (measurement)
1	40 Hz
2	70 Hz
3	141 Hz
4	179 Hz
5	244 Hz
6	262 Hz

- Coupling in measured modes
- Parasitic mode at 40 Hz (mode 1)
- Measured modes 2 and 3 shifted

Potential causes : unglued reinforcement beam , distorted elements

